

X-ray Tomography Applications for Electronics

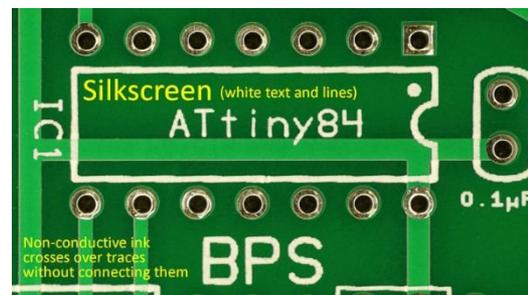
Navid Asadi

Physical Inspection and Attacks on ElectronicS (PHIKS)

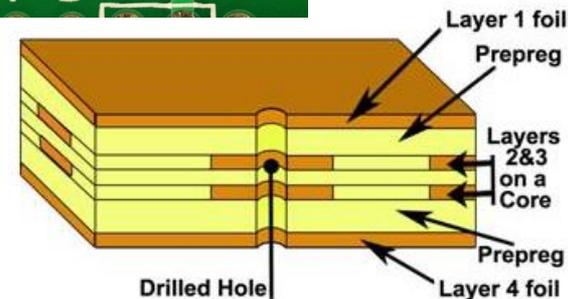


Printed Circuit Boards (PCB)

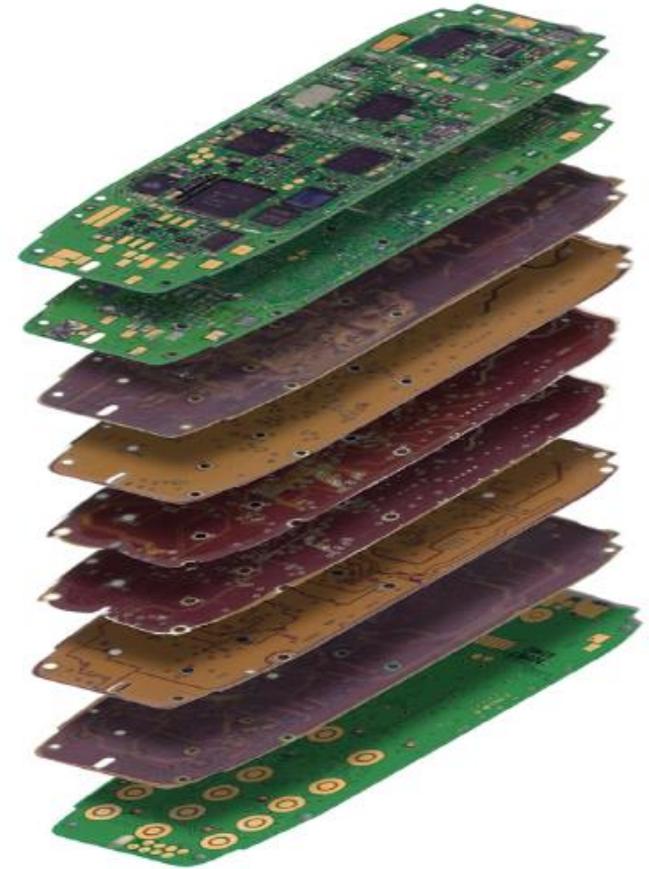
- PCBs and their applications:
 - ✓ Aerospace, Automotive, Medical, Telecommunication, Military, etc.
- PCB Composition
 - ✓ **Conductive** layers are laminated with **non-conductive** layers
 - ✓ PCB's surface is coated with **solder mask**
 - ✓ To identify the components, logos, test points, and parts of the PCB, **silkscreen** markings are often used



Tabtronics.net



- Primary purpose of PCB RE
 - ✓ Identify all components on the board and the connections between them
- Goal
 - ✓ Removing exterior coatings
 - ✓ Accessing individual PCB layers



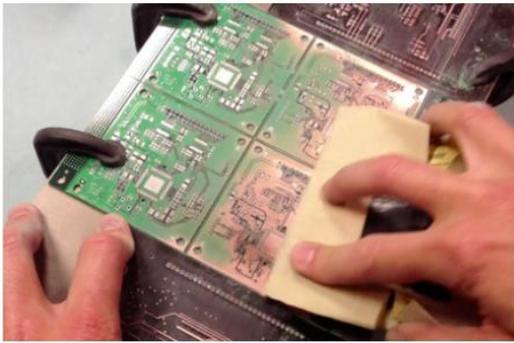
Destructive Methods

1. Solder mask removal
 - Goal is to remove the solder mask from the PCB
 - Expose the copper traces
2. Delayering
 - Access the inner copper layers of a multi-layer PCB by physical destructive methods.
3. Imaging
 - Digital imaging: save connection information of each layer before its removal

Non-destructive Method

1. Computerized Tomography (CT)
 - X-ray imaging method: series of 2D X-ray images are post-processed to create cross-sectional slices of the target object

Solder Mask Removal



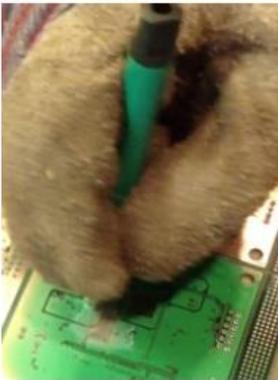
Using Sandpaper



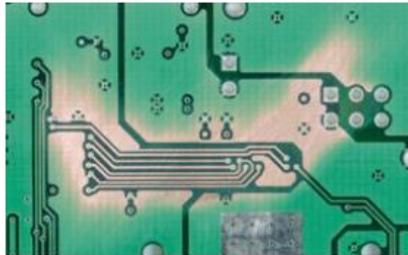
Chemical



Laser



Using Fiberglass Scratch Brush



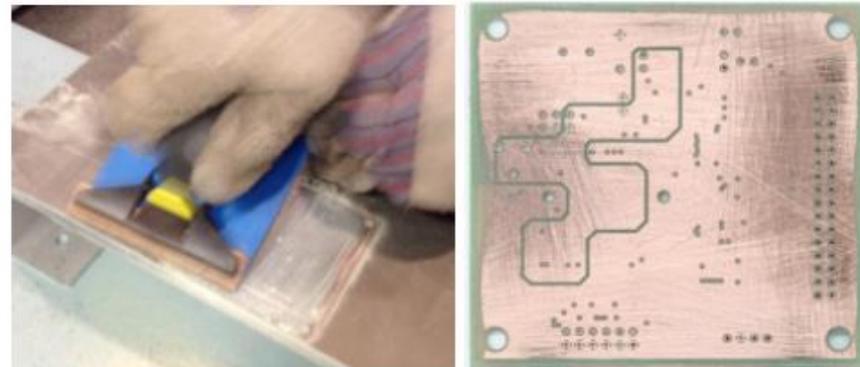
Abrasive Blasting



Joe Grand, USENIX Association, 2014.

Delayering

- Mechanical based delayering is a **time consuming** and **labor intensive** process for material removal



Sandpaper



Dremel Tool



CNC (computer numerical control) Milling

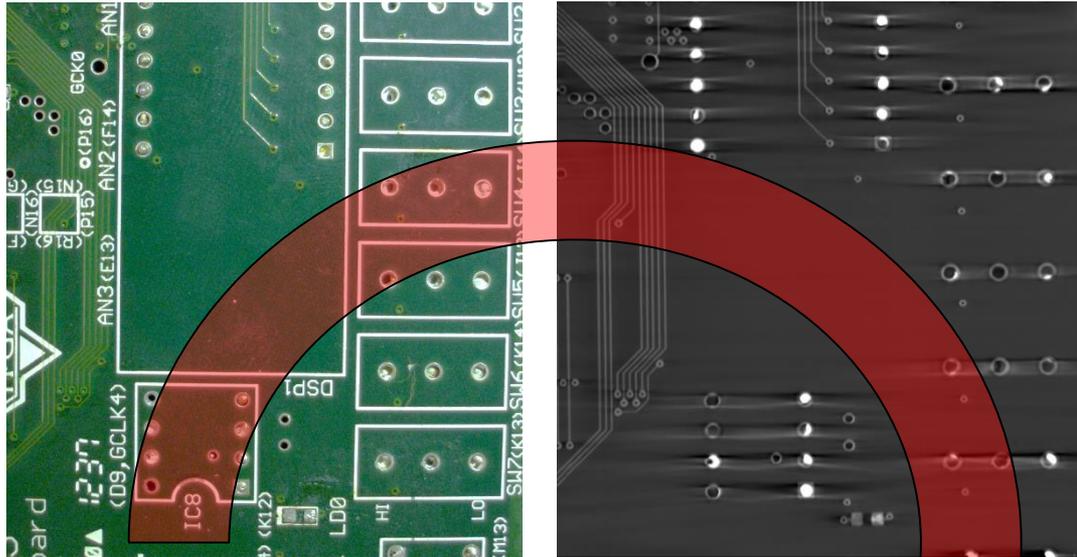


Joe Grand, USENIX Association, 2014.

Automated Non-destructive Imaging Using X-ray Tomography

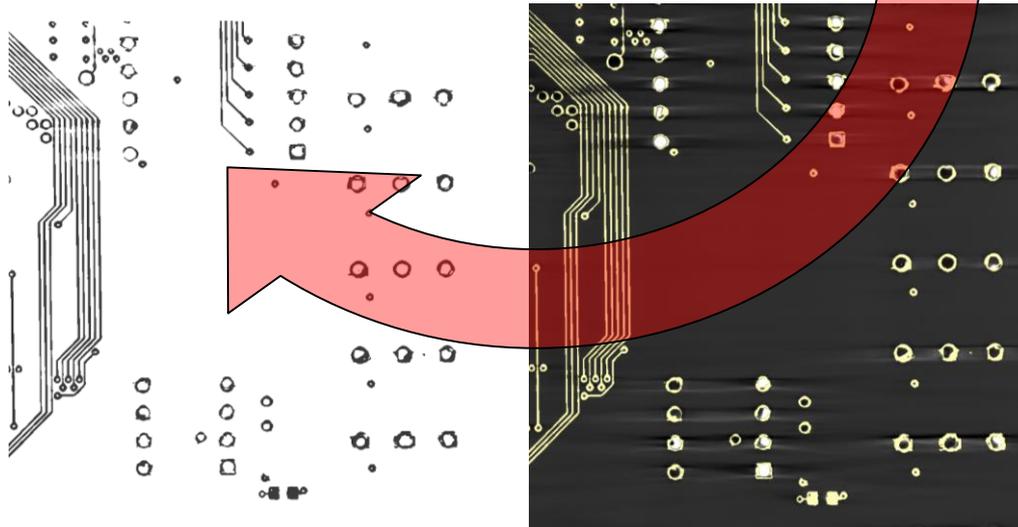
Automated PCB RE Process

PCB



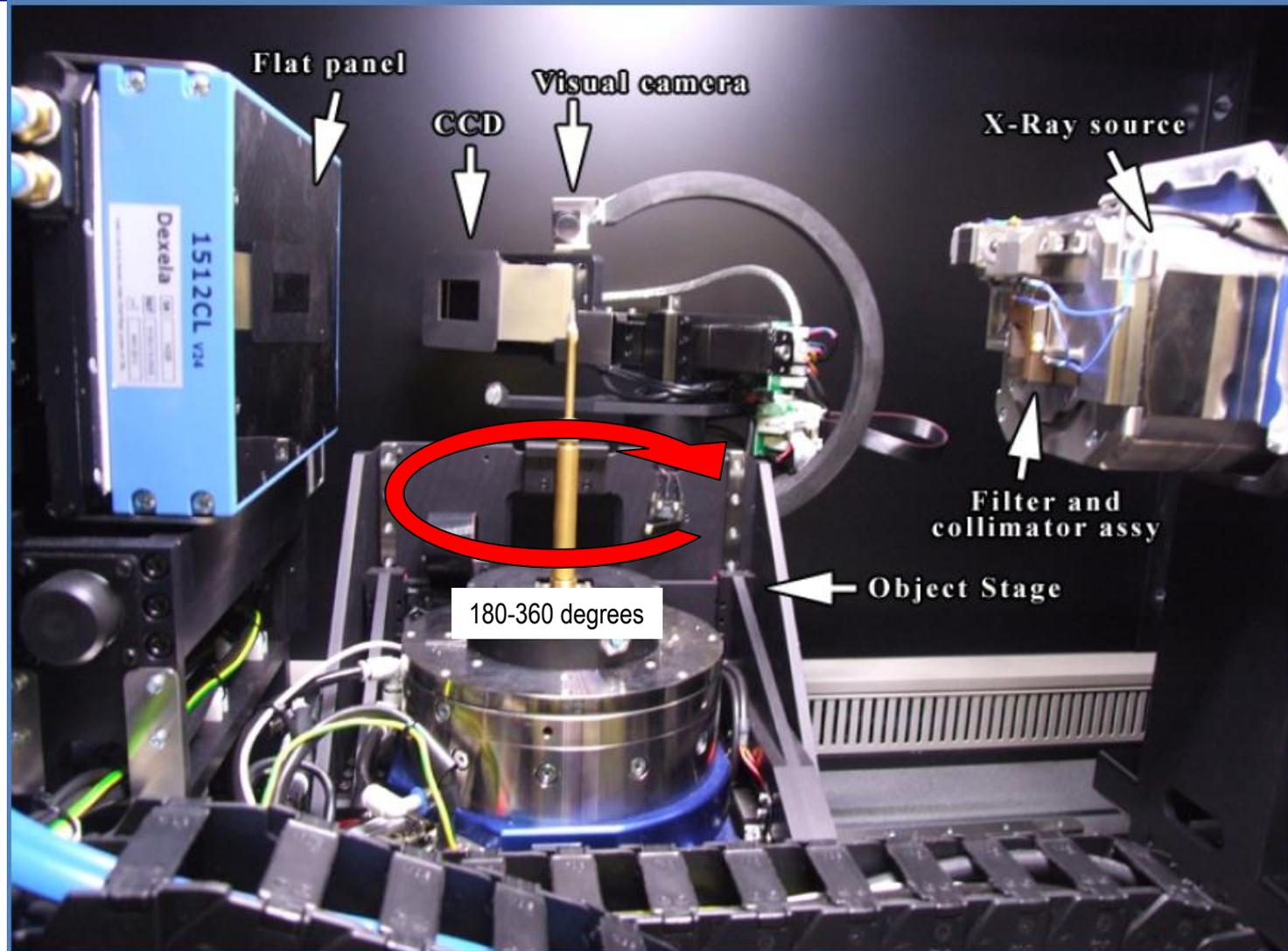
3D X-ray image

DXF or GERBER file

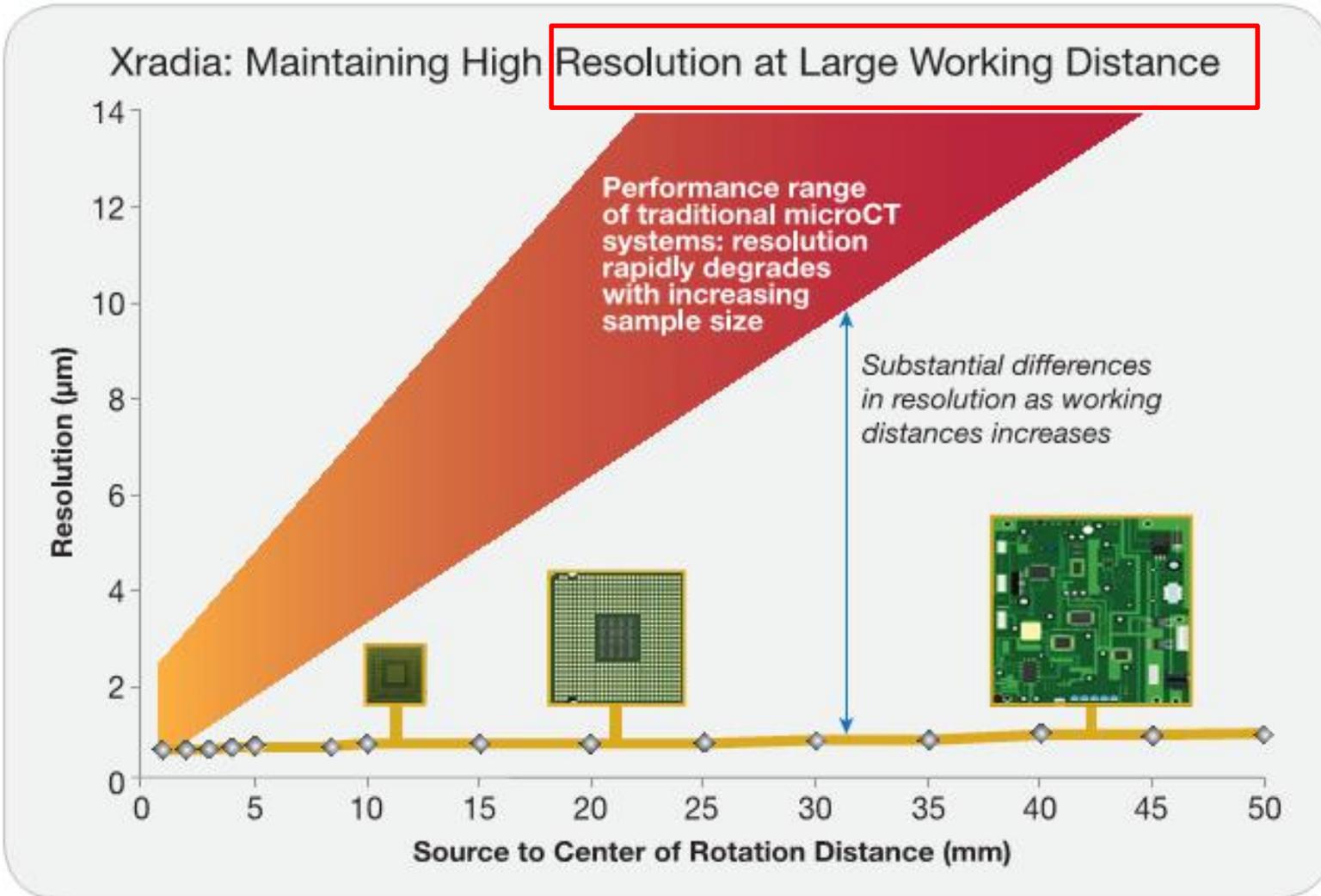


Segmented Image

X-ray Tomography of a Custom Board



Right Instrument for Our Purpose

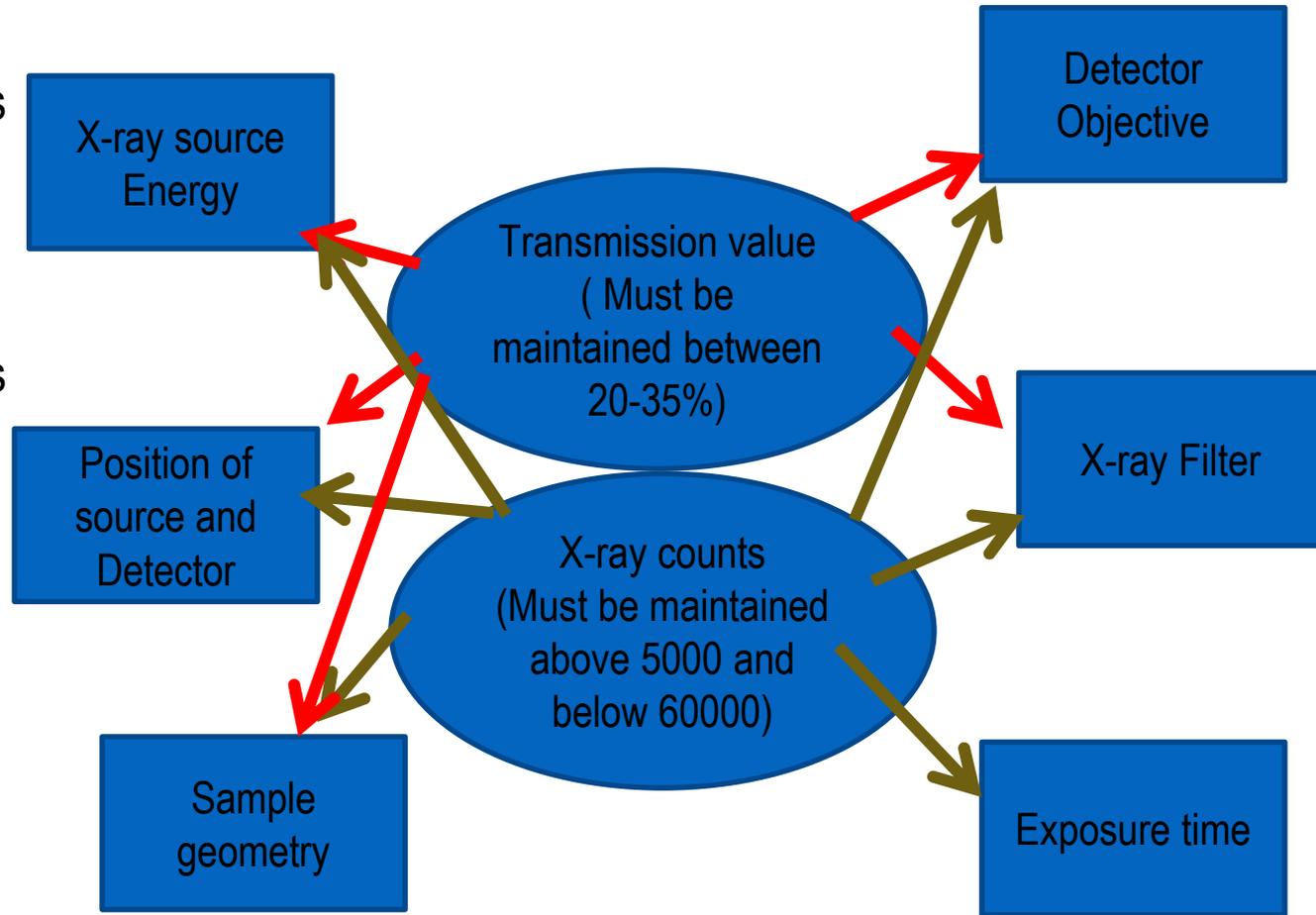


Acquisition Stage

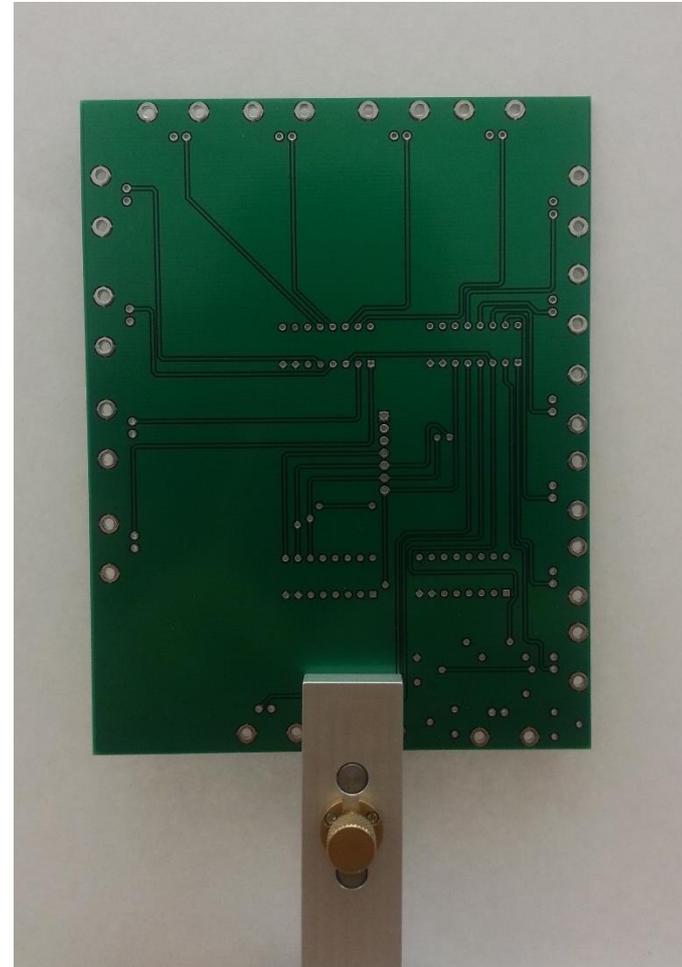
Acquiring X-ray tomography is nontrivial

Tomography costs:

- More than 150 hours of scan have been done for about 50 scans.
- More than 100 hours for image reconstruction.
- Large file sizes, about 2GB for each tomography.



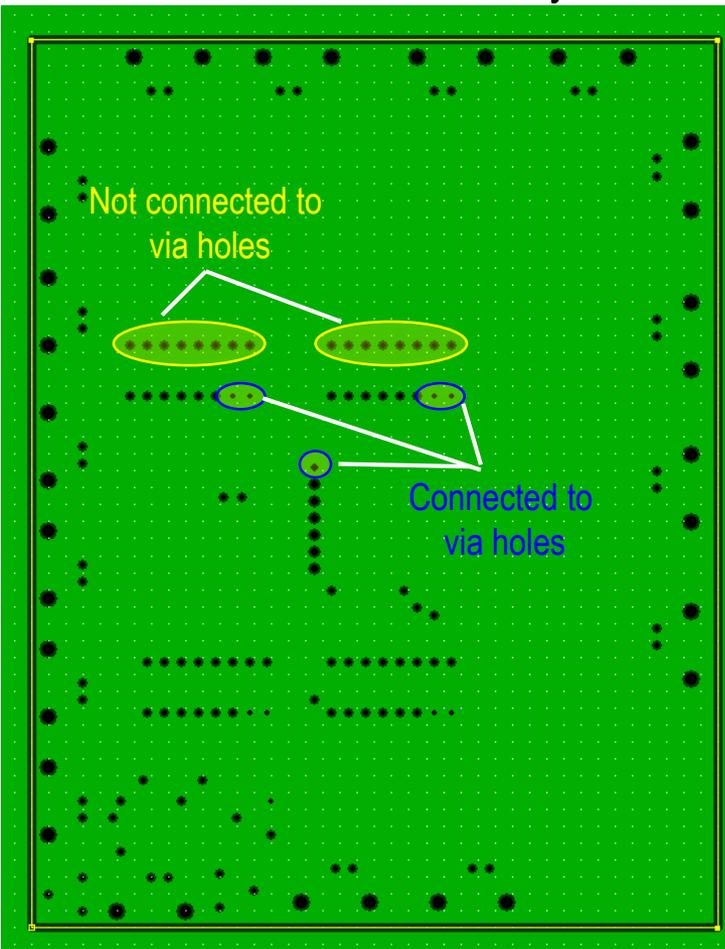
- X-ray tomography parameters have been optimized after several rounds of tests to better capture the intermediate layers structure
- Four layer PCB Including two intermediate layers:
 - Power layer
 - Ground layer
 - Two side layers



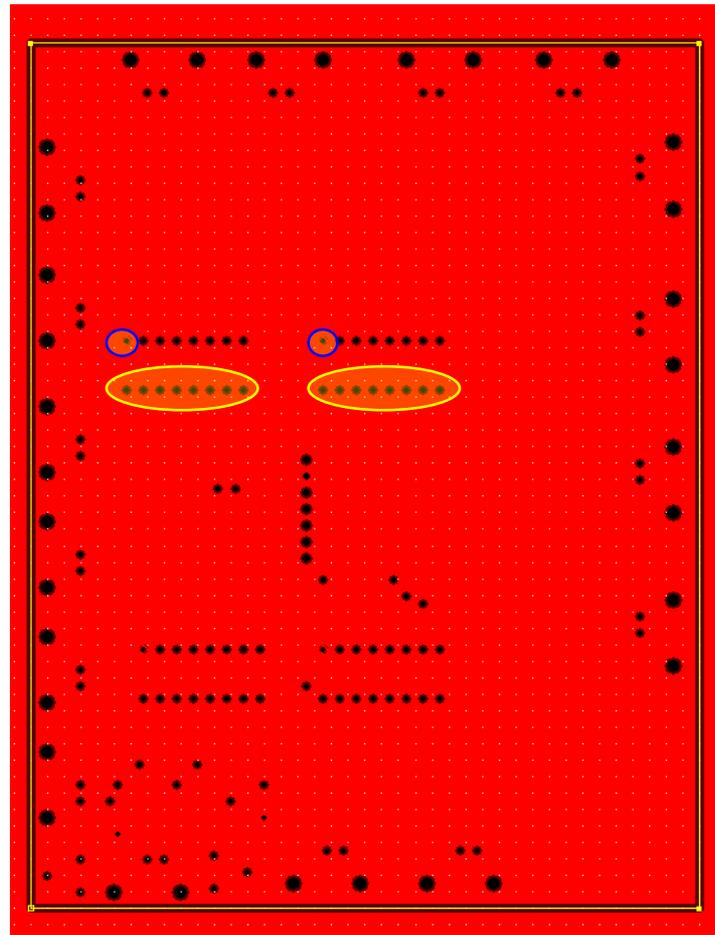
PCB mounted in sample holder

Intermediate Layer's layout

Power Intermediate layer



Ground Intermediate layer

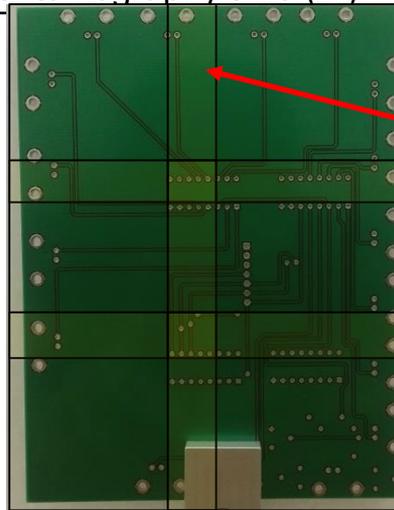


Optimized Tomography Parameters

- **Multiple scans** are taken to cover the complete board.
- **20% overlap** is needed to provide correlation information for **stitching** in the reconstruction step
- **One time set up** is required to run all the scans.

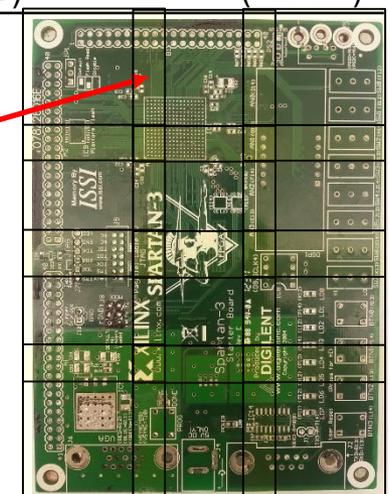
Tomography parameters	Custom board	Spartan 3
Pixel size (μm)	49.2	47.9
Window size (mm)	49.5	48.5
Detector	0.4X	0.4X
Source distance (mm)	204.2	200.0
Detector distance (mm)	80.1	86.0
PCB aspect ratio	10-0.3	14-1.5
Exposure time (s)	1.2-7.2	1.5-9
Number of projections	1601	1601
Number of scanned areas	6	12
Total tomography time (hr)	9 (6*1.5)	18 (12*1.5)

Costume board



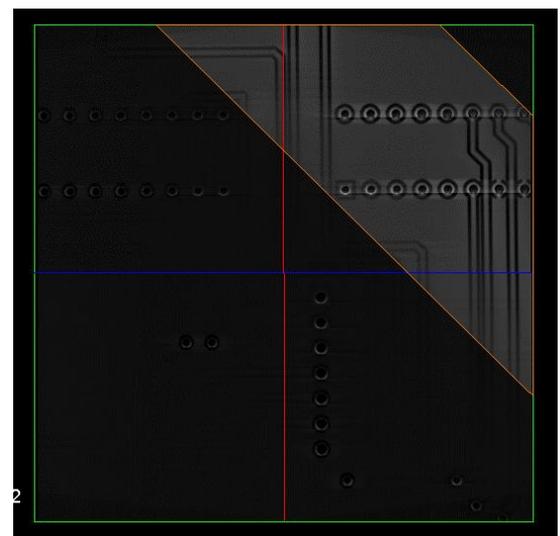
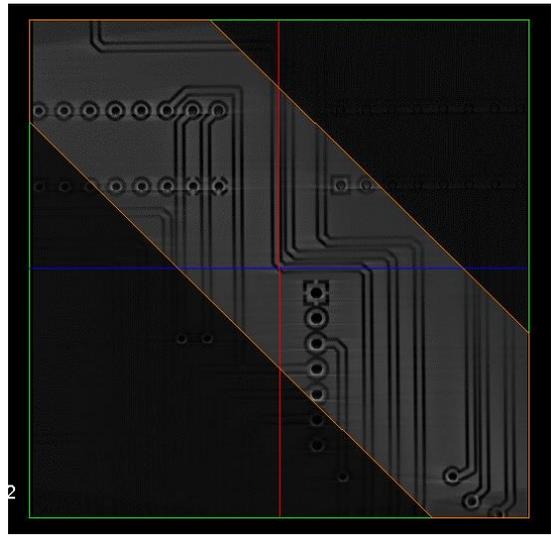
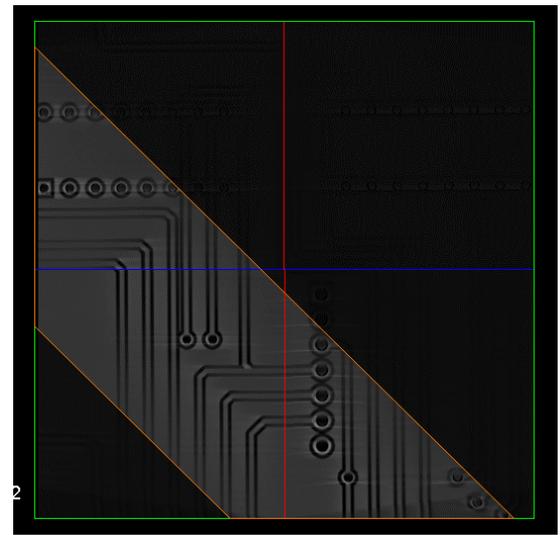
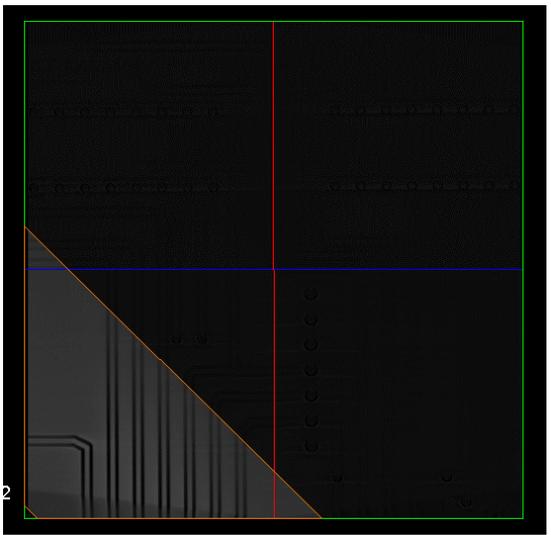
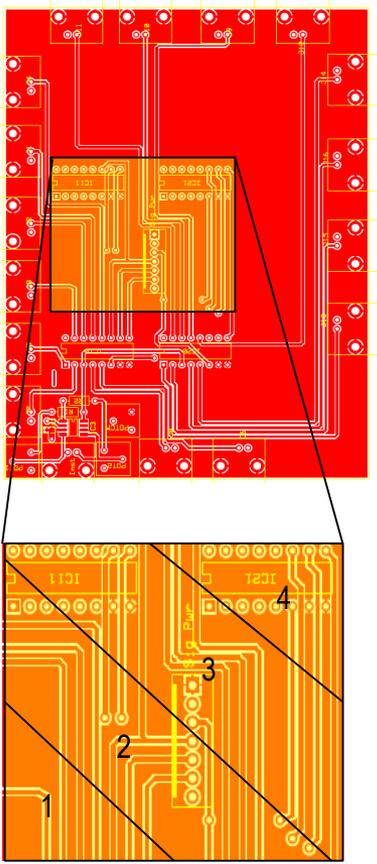
Overlapped areas

Spartan 3



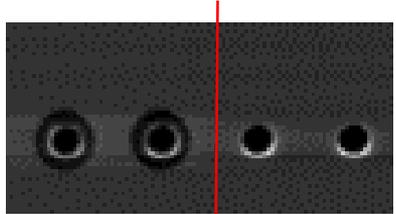
Layer #1

Imaged Area



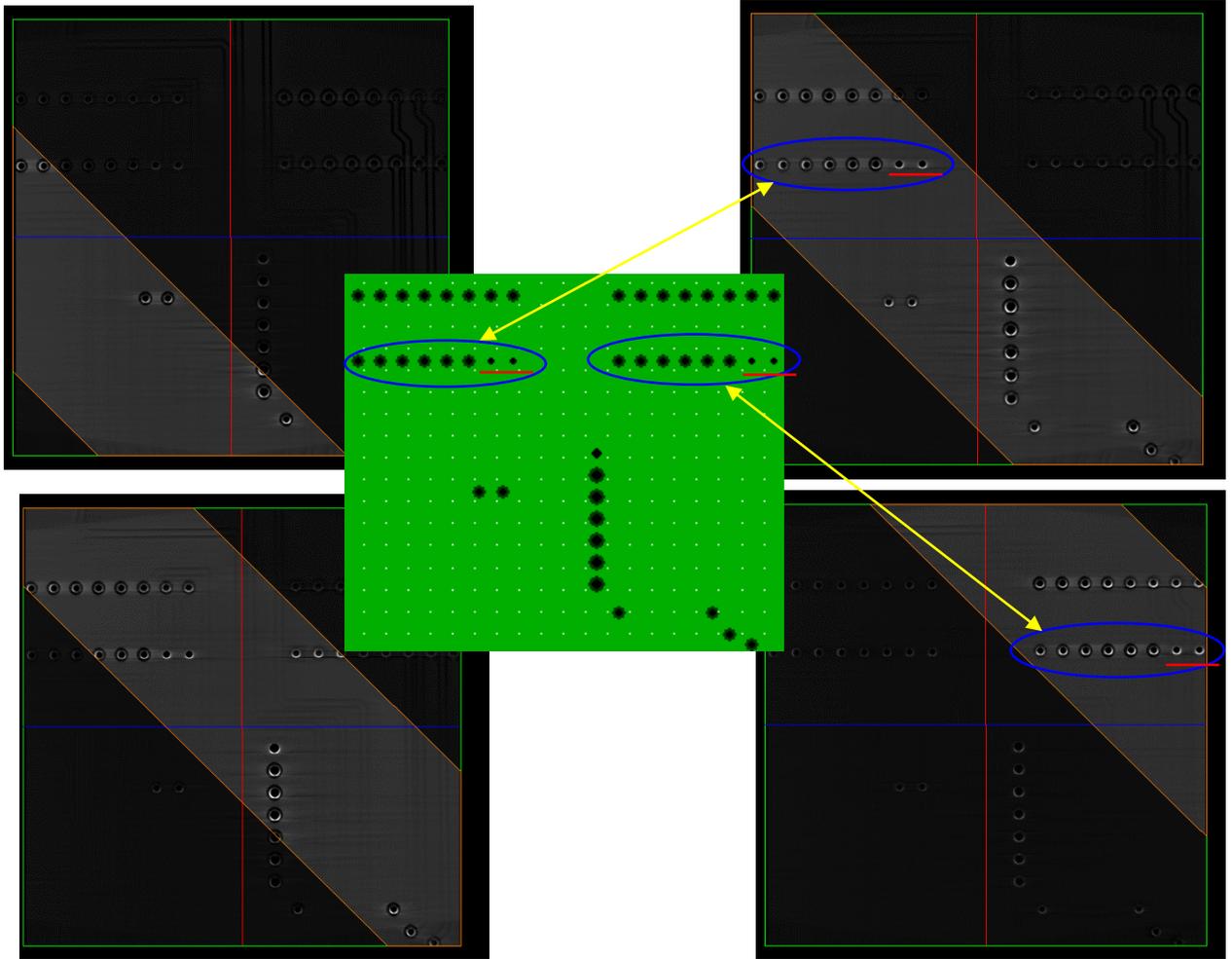
Layer #2, Power Layer

Connected and not connected via holes captured with X-ray

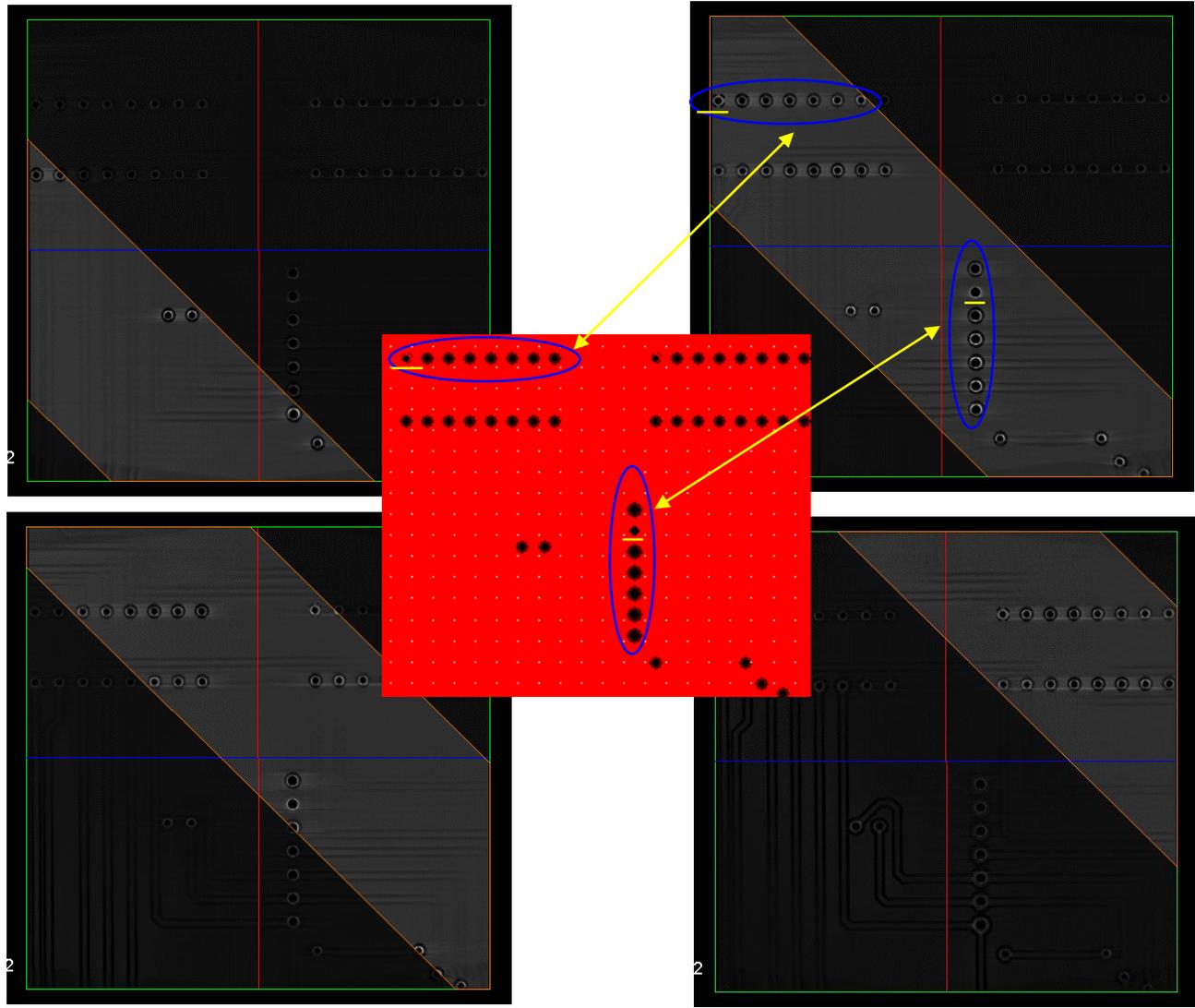


Not connected

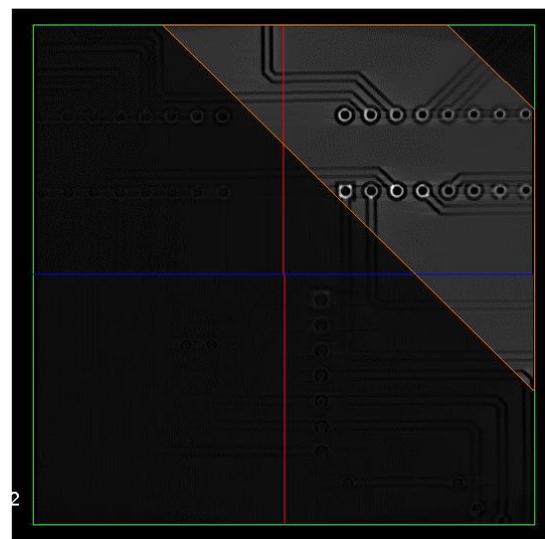
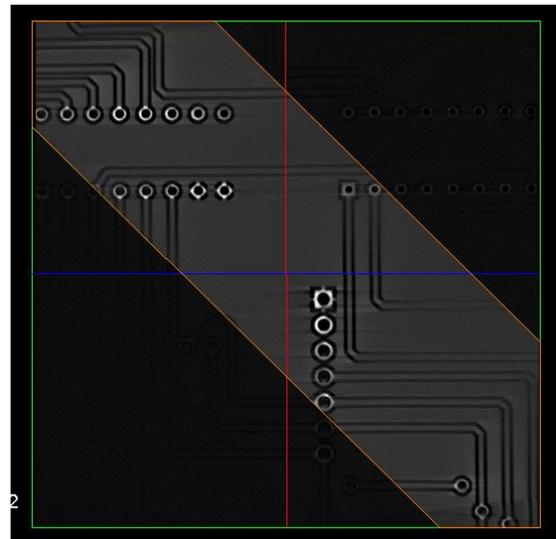
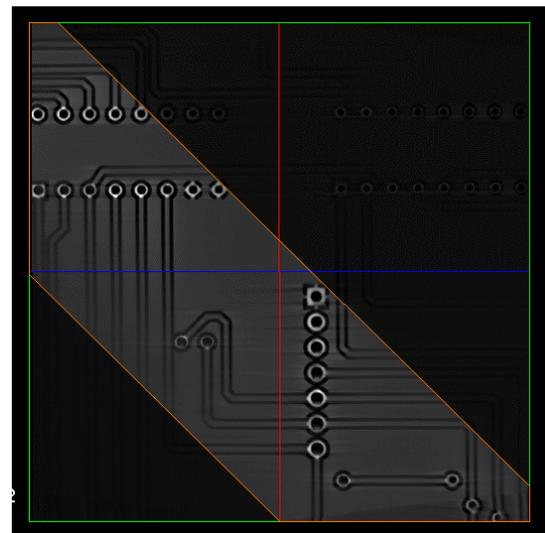
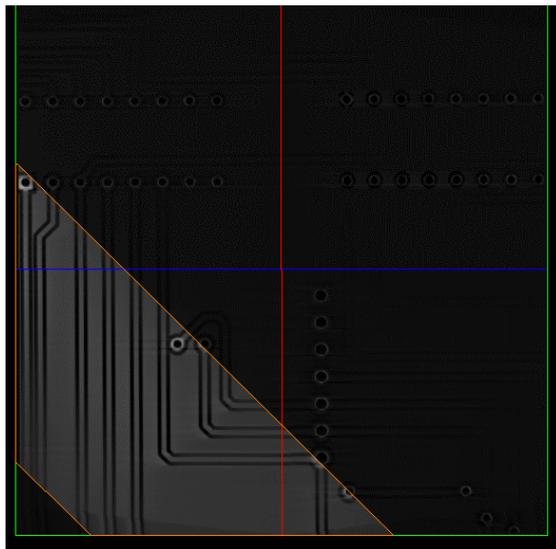
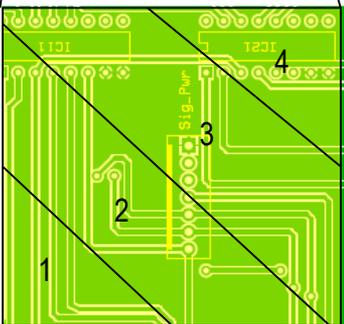
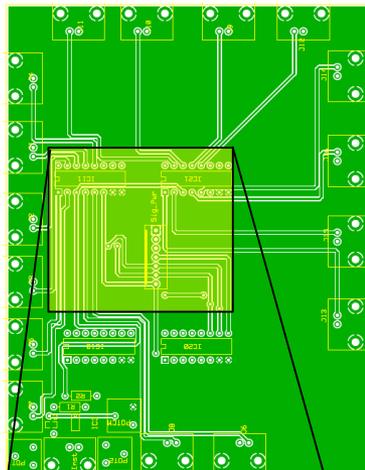
Connected



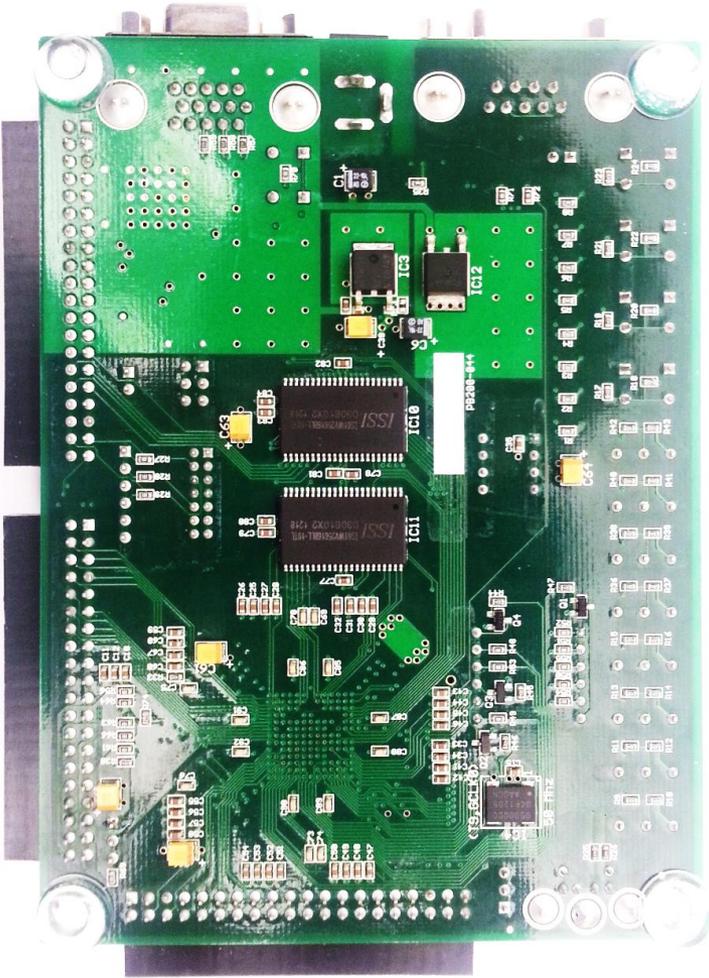
Layer #3, Ground Layer



Layer #4, Bottom



RE of a Commercial PCB



Xilinx Spartan 3

6 layers PCB
2 layers for
ground and
power

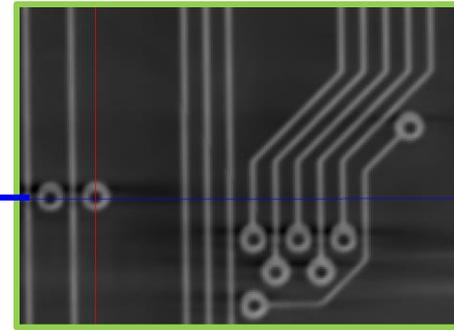
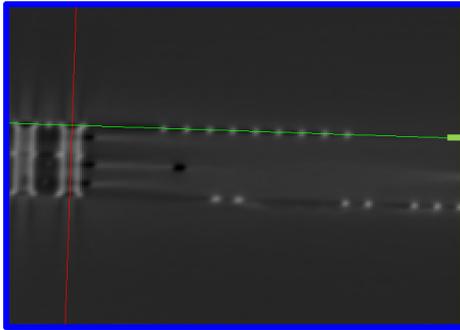
Front view →

← Back view

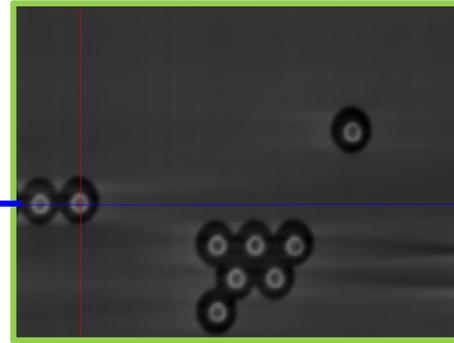
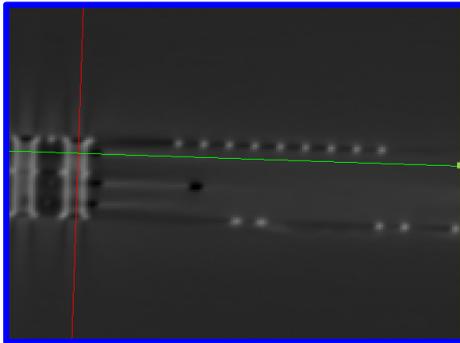


Spartan 3 Layers 1-3

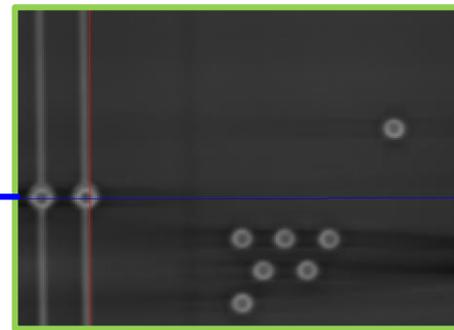
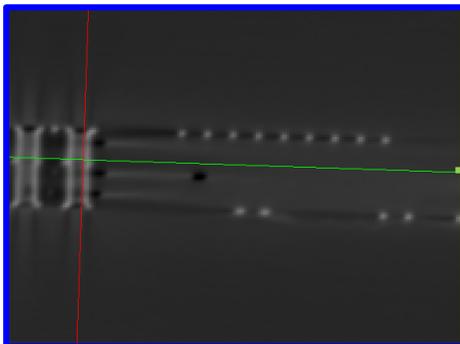
Layer 1



Layer 2

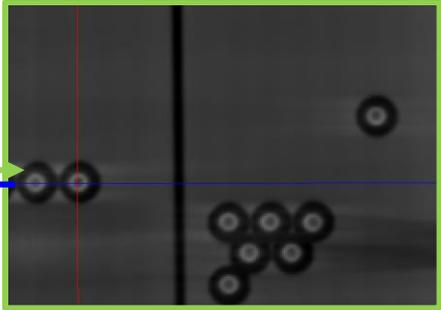
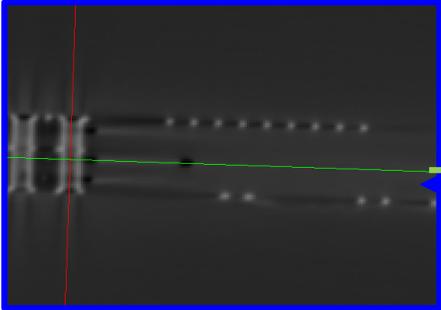


Layer 3

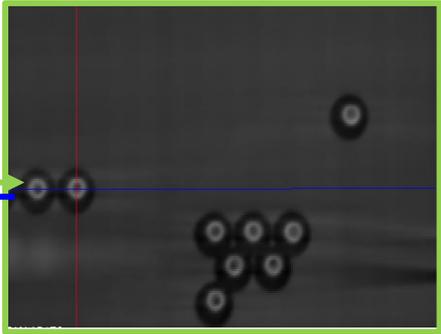
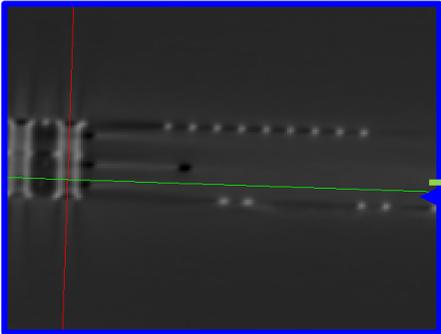


Spartan 3 Layers 4-6

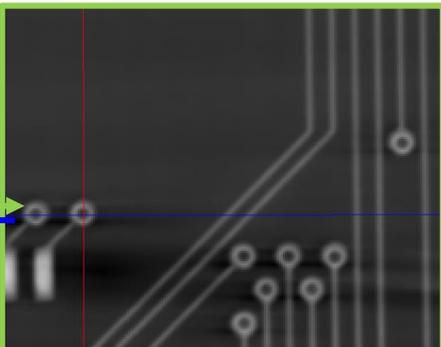
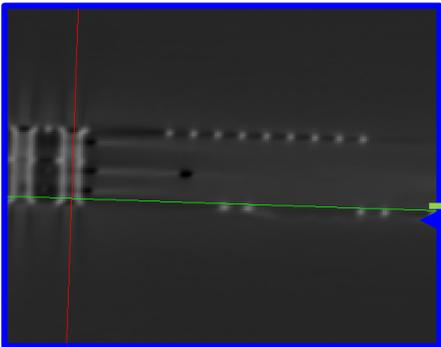
Layer 4



Layer 5



Layer 6



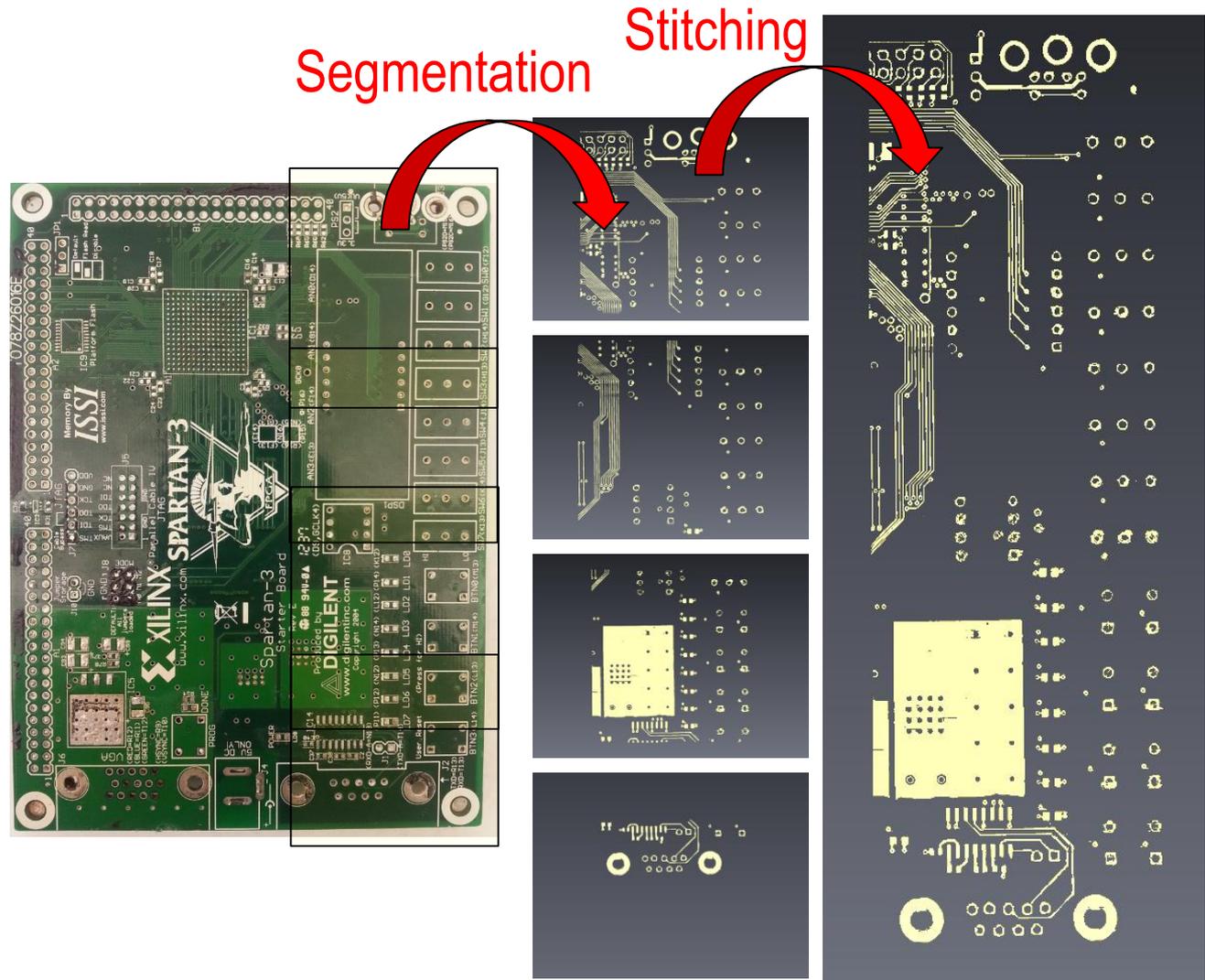
Generating CAD Files

Segmentation:

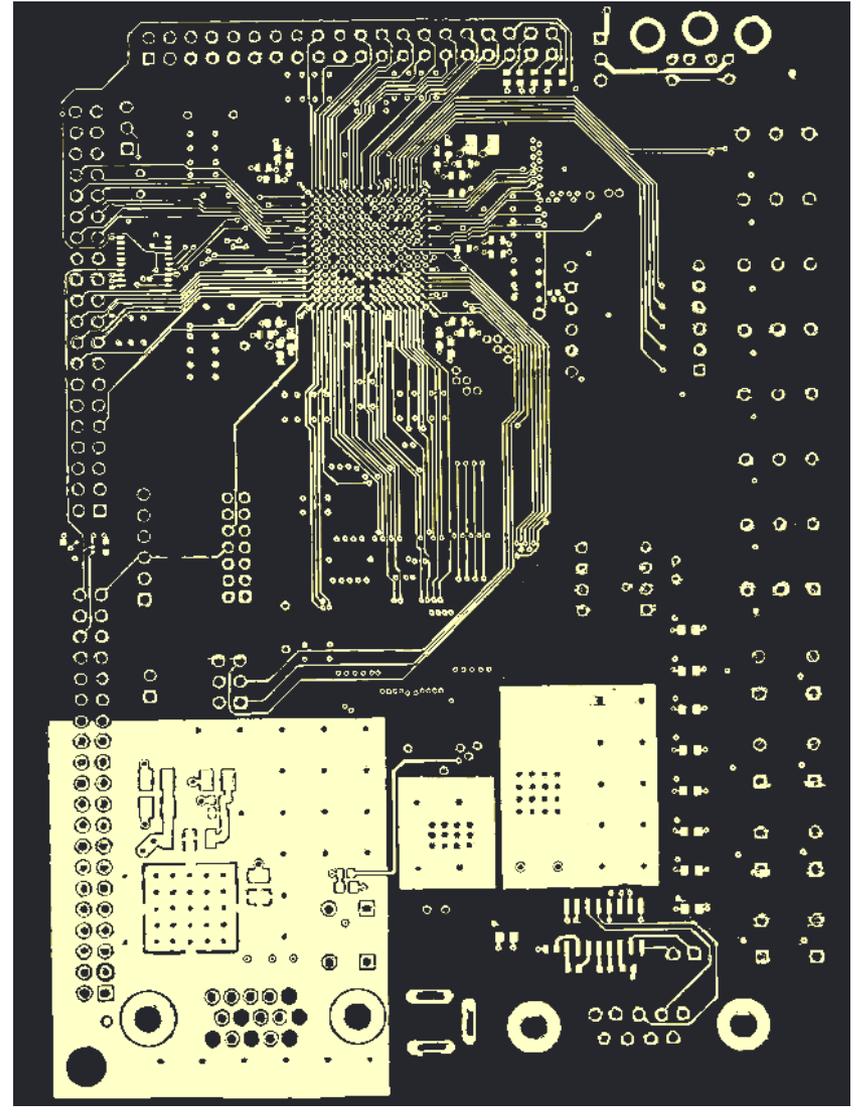
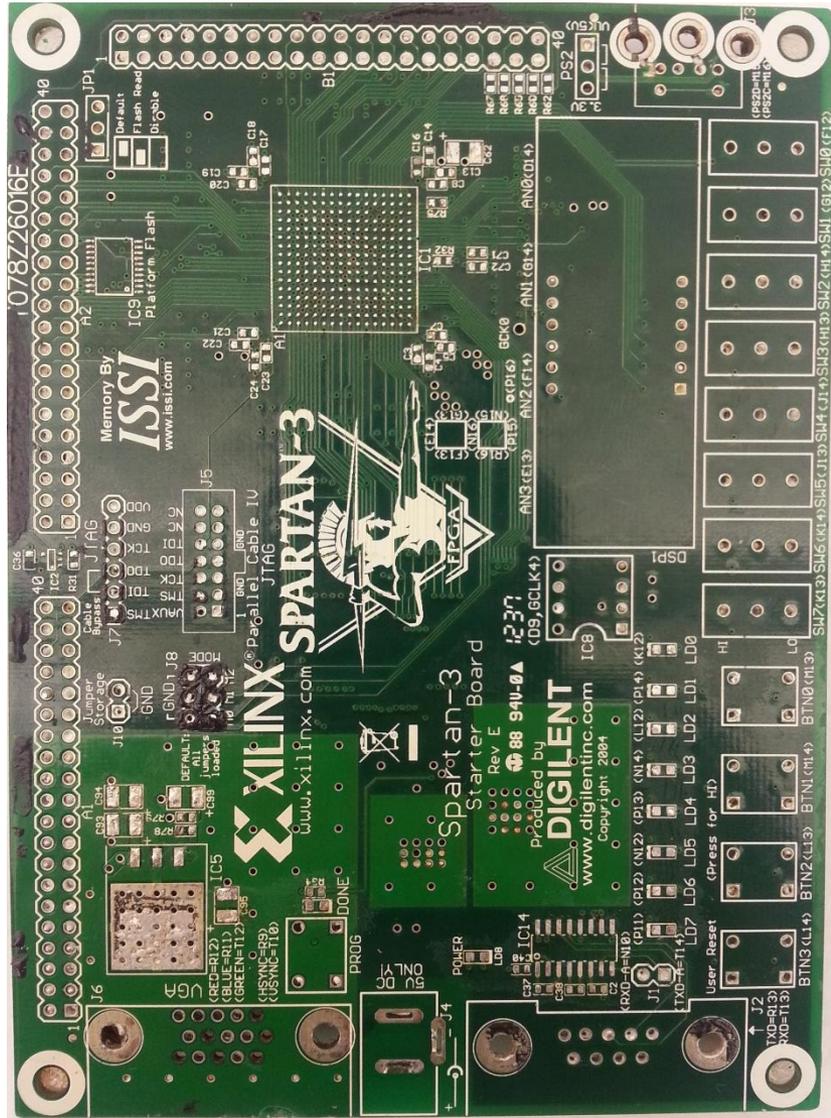
1. Smooth images to minimize noise
2. Assigning material to each pixel based on pixel contrast for segmentation

Stitching:

- Using the features in the overlapped region to correlate two images and merge.

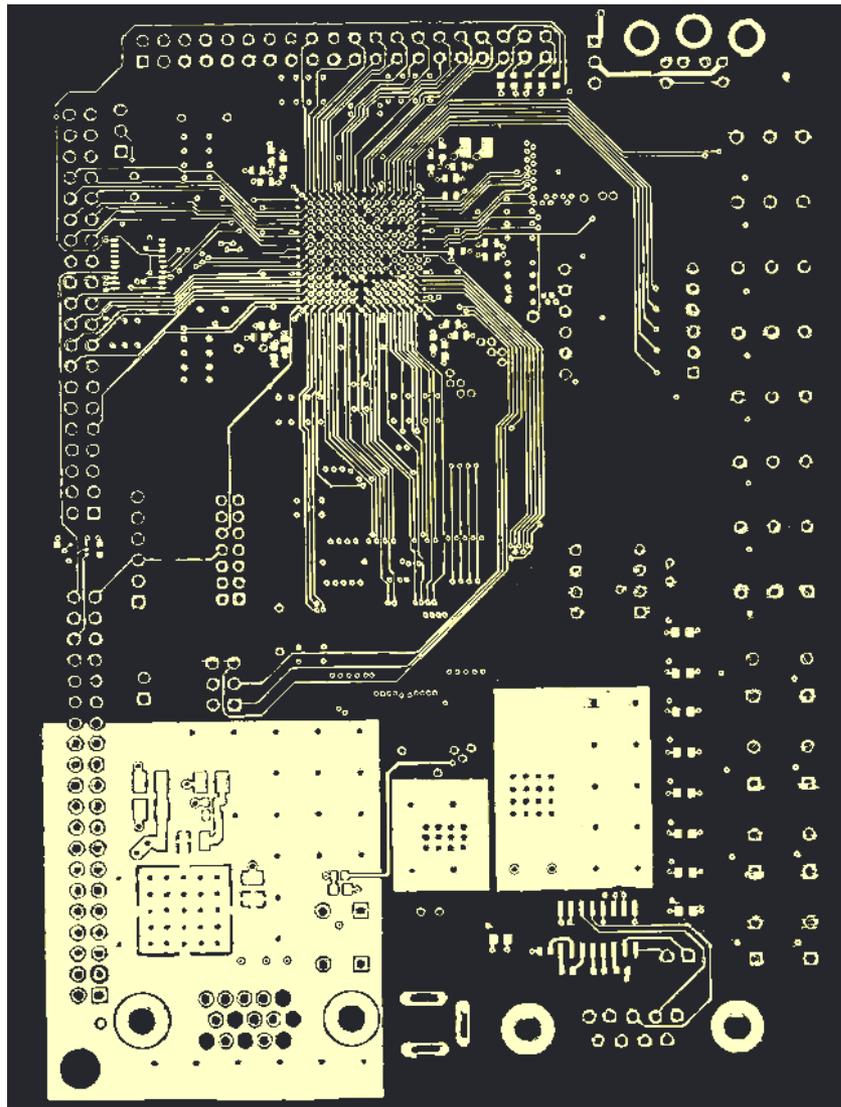


Complete Layer Segmented



Segmented Layers 1-6

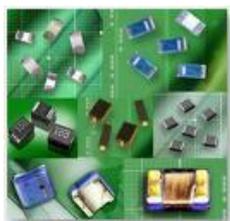
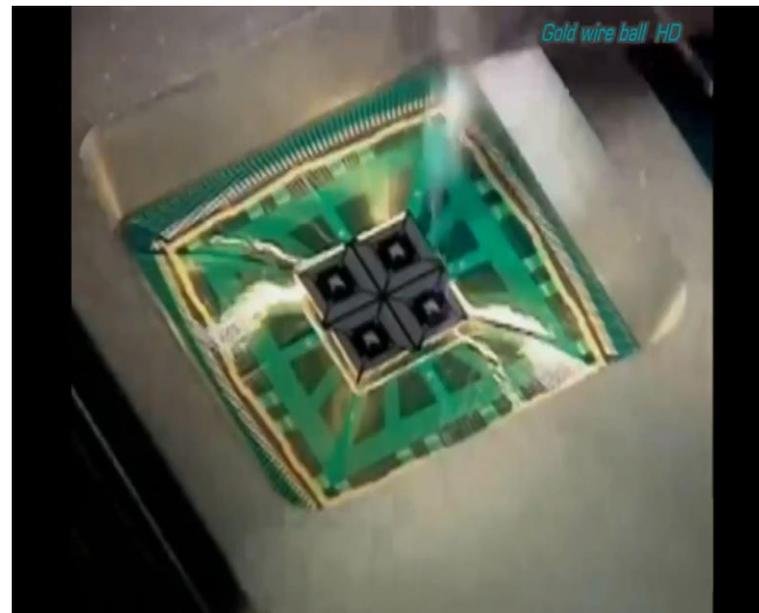
Layer 1



Virtual Bond Pull and Ball Shear Analysis

Bond Wire Quality and Assurance

- 95% of integrated circuits use wire bonding (gold, aluminum, etc.)
- Higher grade microelectronics require better standards for harsh environment
- Quality and assurance requires monitoring breaking force



Chip Package Decapsulation

- Manual grinding and polishing
- Chemical decapsulation
- Abrasive blasting
- Plasma Etching
- Laser decapsulation



Methods above require expert skill, and cost a lot of time and money



VarioEdit Laser Assisted Chemical Etching tool

- Price : \$750K
- Can performs local decapsulation using laser

Destructive Bond Wire Pull Test



Current sample 13 03/27/2013 10:01

Sample	Seq	Dis.	Grading	%	Peak force [kgf]	Remark	User na
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Abs [µm] X: 175509.8 Y: 126685.5 Z: 61510.2 Home Abort
Rel [µm] X: 175509.8 Y: 126685.5 Z: 61510.2 Zero
Pull test step 9, pulling 5000 [µm] 50 \$ Pull 10 kgf

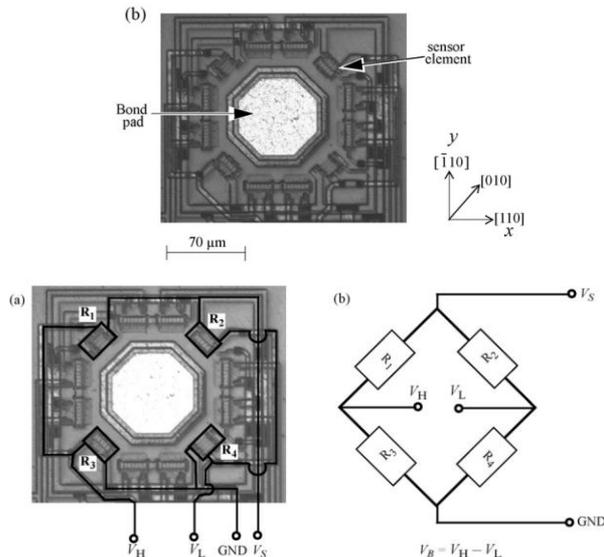
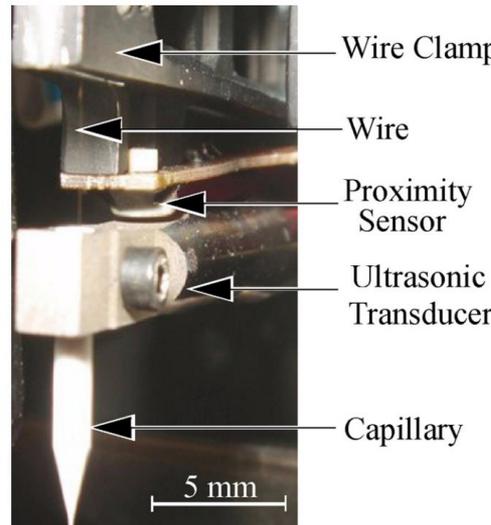
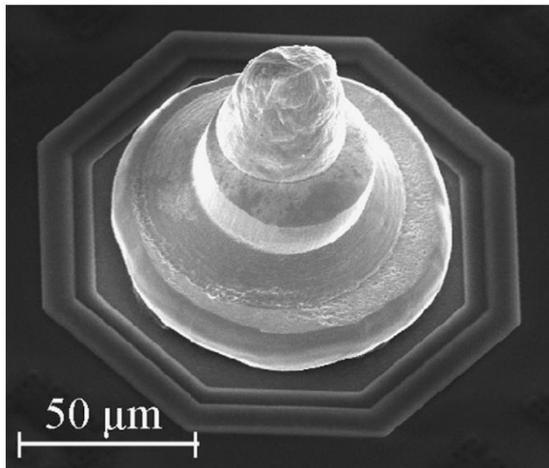
XYZTEC

Condor Sigma

3.2 Wire pull test-thick

Online Force Measurement

- Piezoresistive microsensor** integrated next to the bonding pad
 - The Au wire breaks at the heat-affected zone (HAZ) next to the ball bond
 - Microsensor signal is highly sensitive to **ball and pad geometry, values of the piezoresistive coefficients, and the z-location of the microsensor** under the bonding pad
- Proximity sensor** attached to the wire clamp of the bonding machine
 - A displacement sensor works on the eddy current principle to sense proximity of conductive materials



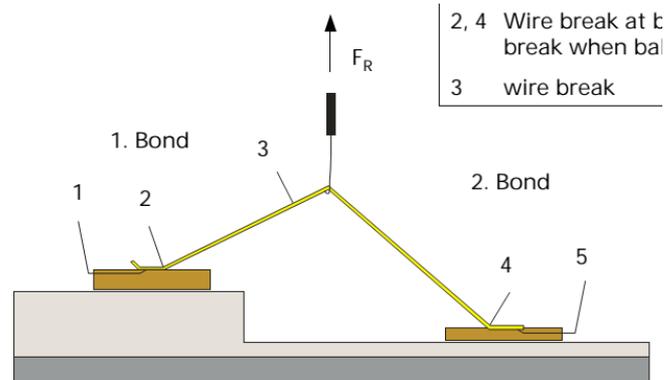
Aashish Shah et. Al. 2008

Actual Mechanical Testing



Failure modes:

- 1, 5 Bond lift off from pad metallization (lift off)
- 2, 4 Wire break at bond (heelcrack or neck break when ball/wedge bonding)
- 3 wire break

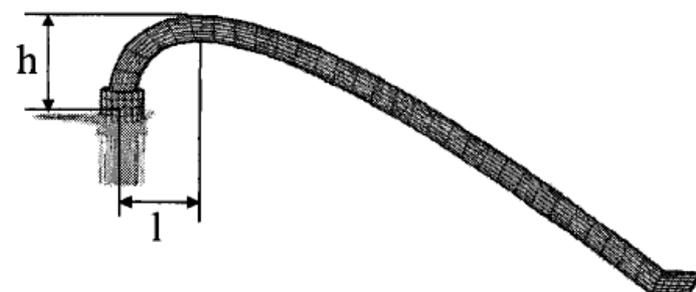
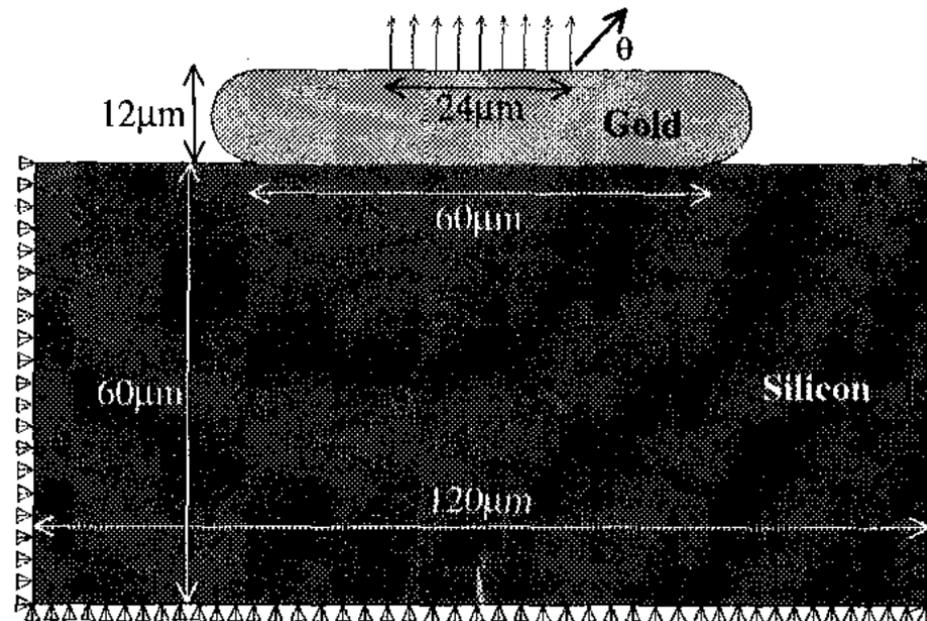
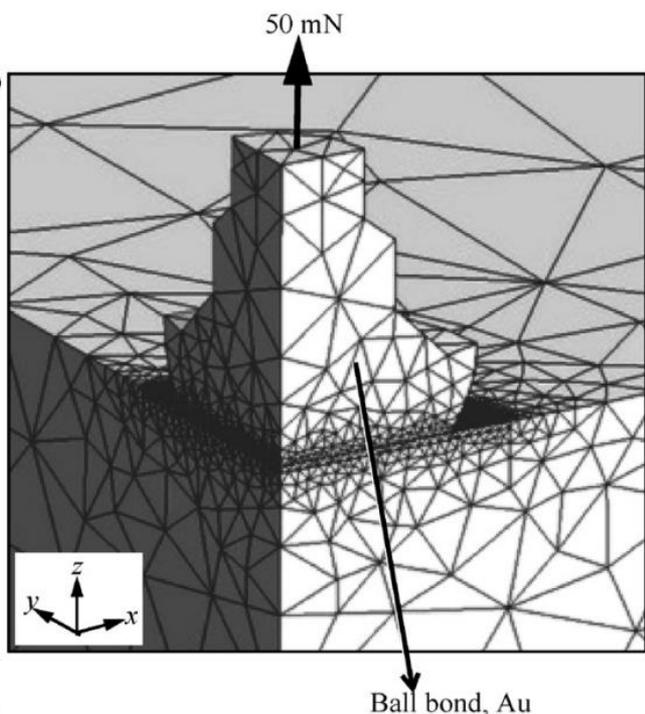


Disadvantages

1. **Package** should be entirely or at least partially removed
2. Each wire can be used for **only one test**
3. **Durability and Fatigue** Analyses require long testing times
4. The effect of mechanical load is exerted on **one wire** at a time

FE Simulation Challenges

- **Not necessarily representative** of the real geometry and structure of wires
- Modelling efforts have utilized **2D SEM** images



Geometry Simplification is inevitable while modelling a **3D structure**

Tomography parameters for microchips

	TL 145406N	AD7512DIJN
Magnification	35.94	37.98
Voxel size (μm)	5.56	5.26
Focus-Object-Distance (mm)	22.39	21.2
Focus-Detector-Distance (mm)	805.22	805.22
Number of projections	1200	1200
Source voltage (kV)	200	200
Source current (μA)	25	25

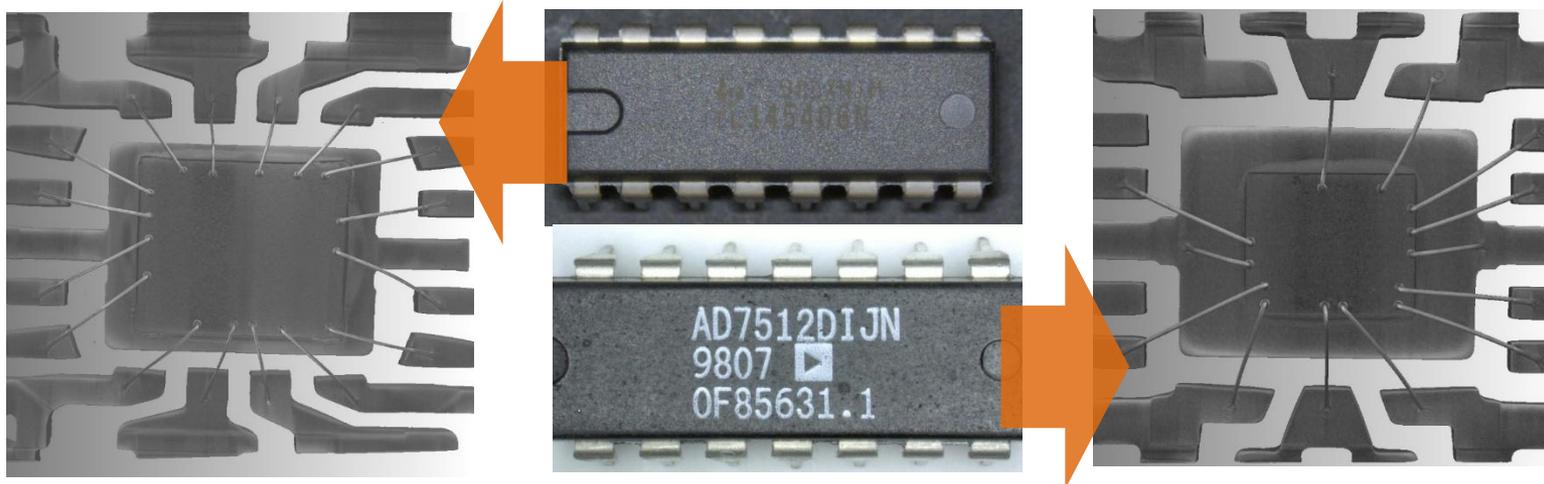
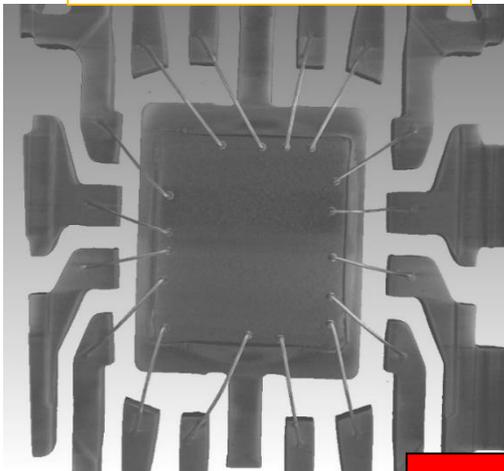
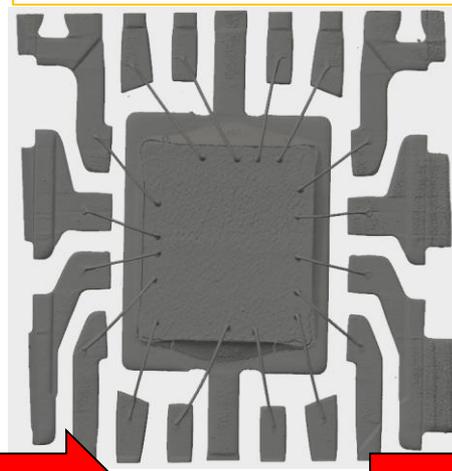


Image Filtering and Segmentation

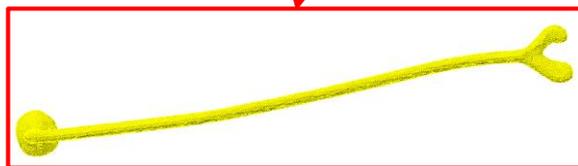
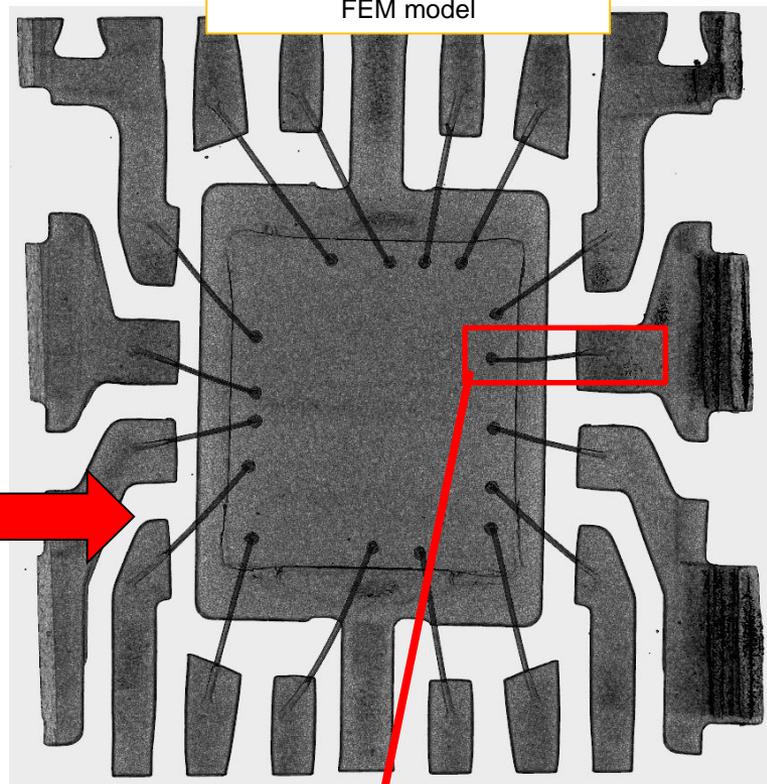
Visualized 3D Data



3D CAD data after segmentation



FEM model



Quantitative analysis

Filtering

- Remove **beam hardening** effect
- Smoothing and denoising images

Segmentation

- Assign material to each pixel based on their contrast.

FE Model Information

There are three different types of bond wire failures:

1. Wire break at bond heelcrack or neck break on ball bond or stitch side.
 2. Wire break that occurs on any place other than the previous two cases.
 3. Bond lift off from pad metallization on ball bond or stitch side. (X-ray resolution is not enough to resolve the details for this item.)
- The first two can be easily detected using the proposed method
 - Autodesk Simulation Mechanical 2017 software is used for quantitative analysis

loop-part (l), loop-height (h)

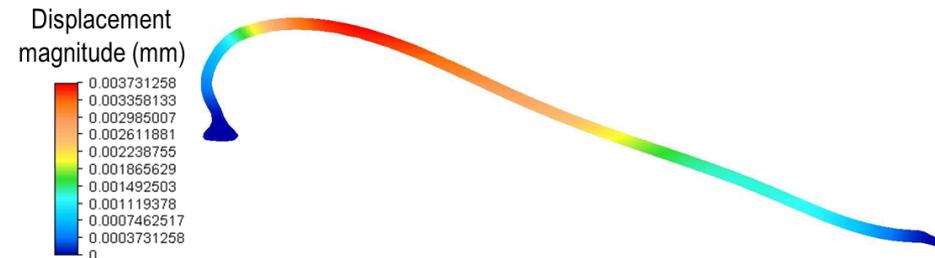
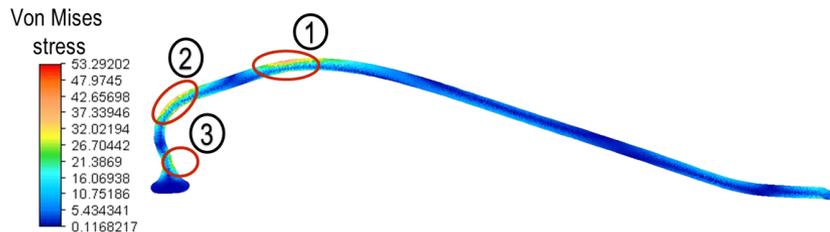
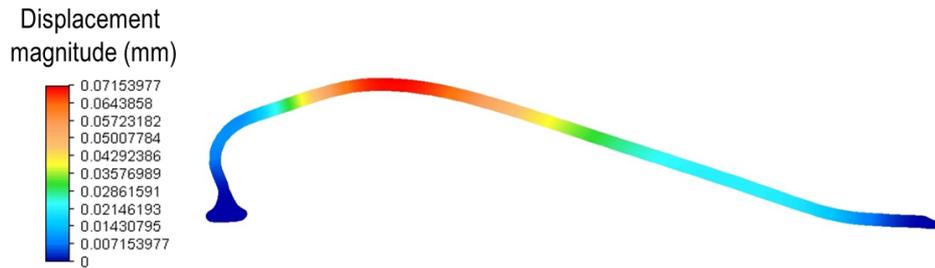
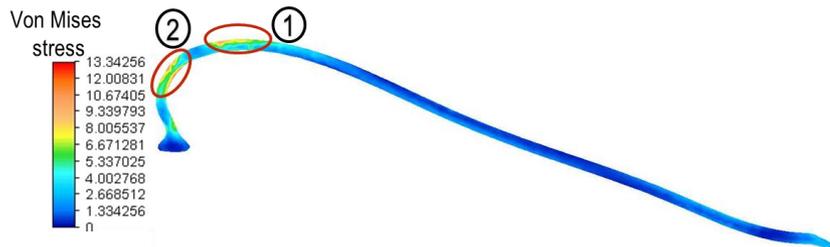
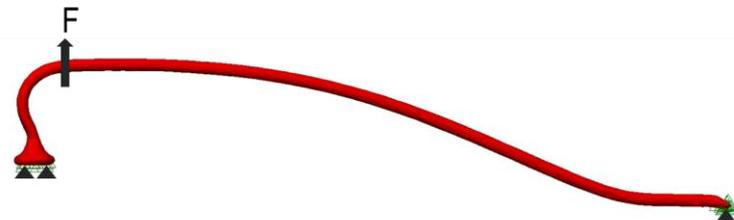


Bond wires meshing information

Chip type	TL 145406N		AD7512DIJN	
	Wire 1	Wire 2	Wire 1	Wire 2
Mesh size (μm)	6.1	6.8	16.1	18.09
Total elements	40468	34195	10225	5154
Total nodes	9855	8526	3047	1664
Loop-part (μm)	30	29	72	46
Loop-height (μm)	179	183	254	257
Diameter (μm)	26.4	23.7	31.2	30.3

FE Analysis

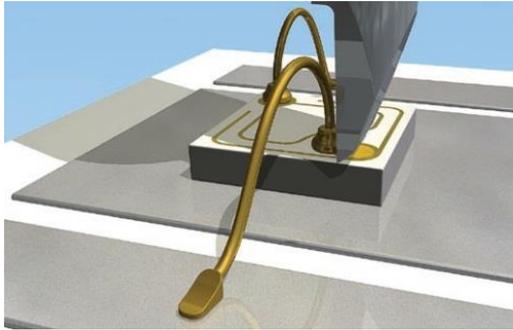
- Initial and boundary conditions are applied to bond wires
- Both ball bond and stitch side are fixed
- 1 cN Load is applied to the bond wire
- **Stress and strain in wires are investigated after applying the force**



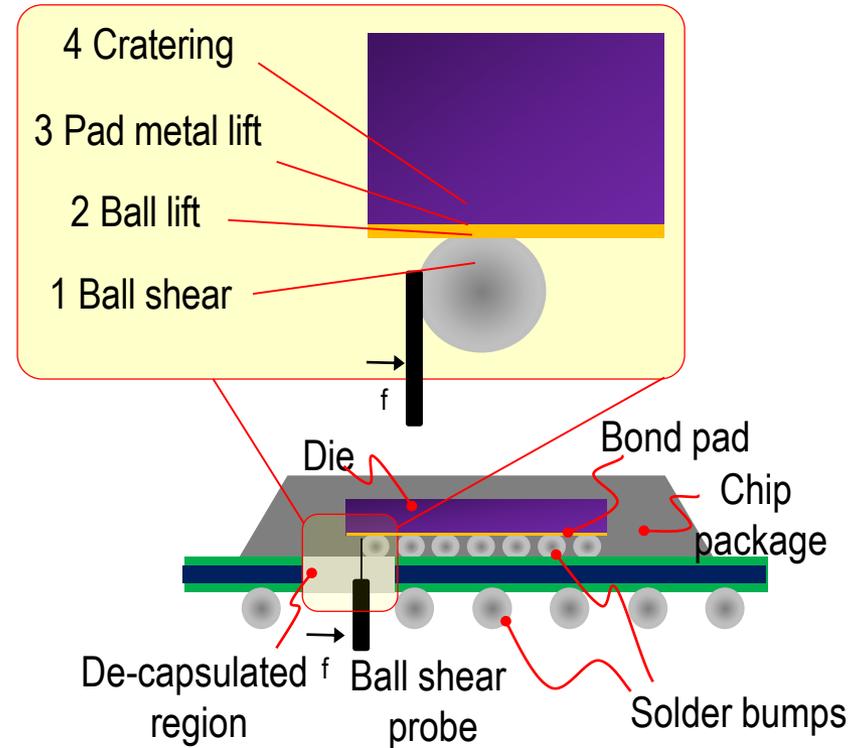
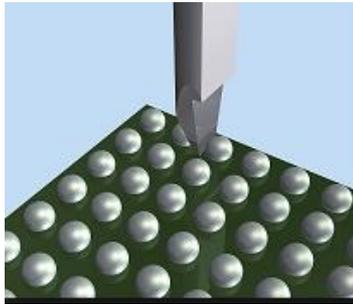
Maximum values for stress and strain are still in an acceptable range

Extension to Ball Shear Testing

Ball bond shear on bond wire



Ball bond shear on ball grid array



Disadvantages

1. **Package** should be entirely or at least partially removed
2. Each ball bond can be used for **only one test**
3. **Durability and Fatigue** Analyses require long testing times
4. The effect of mechanical load is exerted on **one bond ball** at a time

X-ray Tomography Reliability

Experimental Setup

- Selected Integrated Circuits are:

1. Flash Memory

- Intel 28F400B5 (400nm Technology)
- Macronix MX29F400C (150nm Technology)

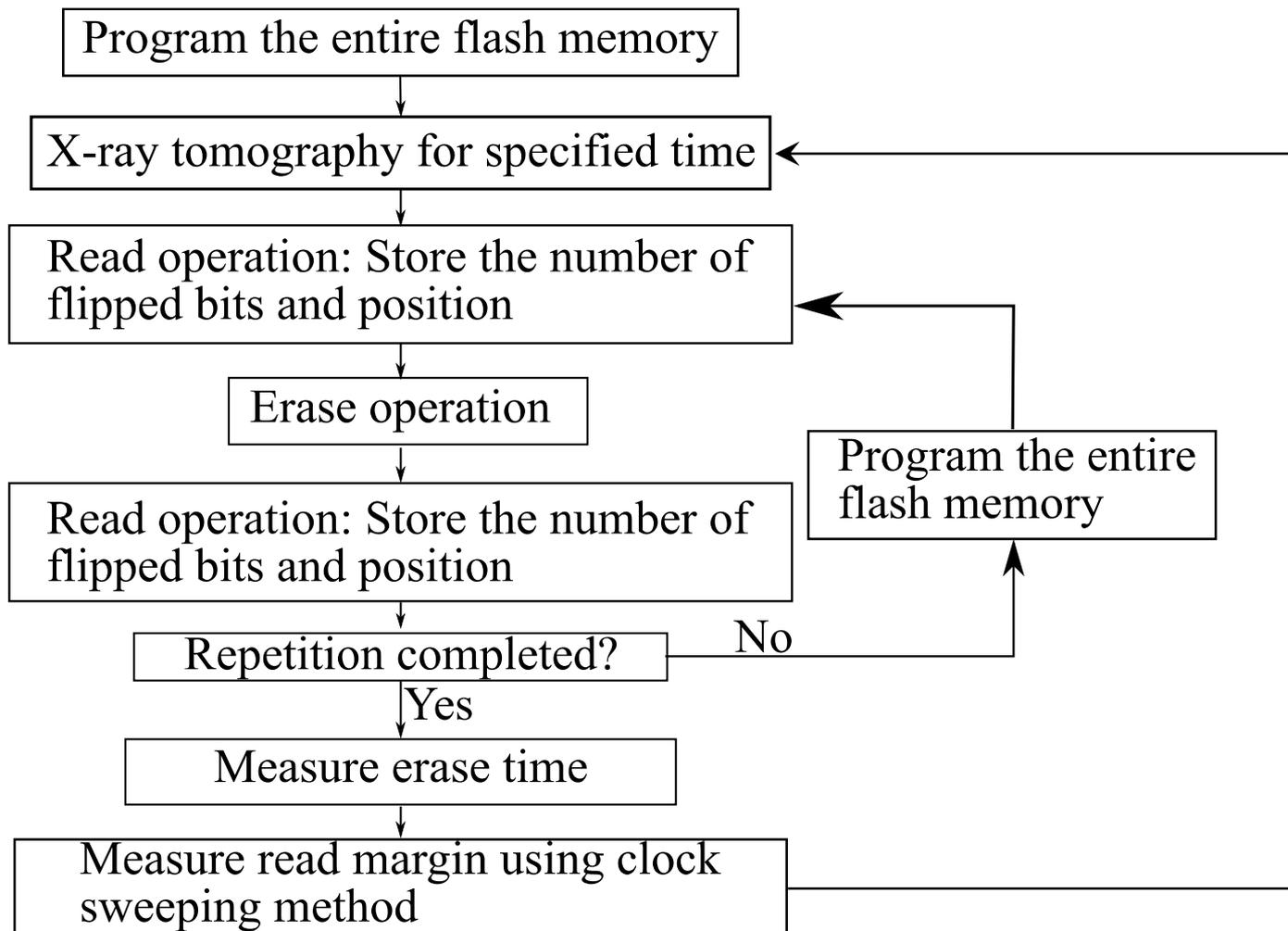


2. FPGAs

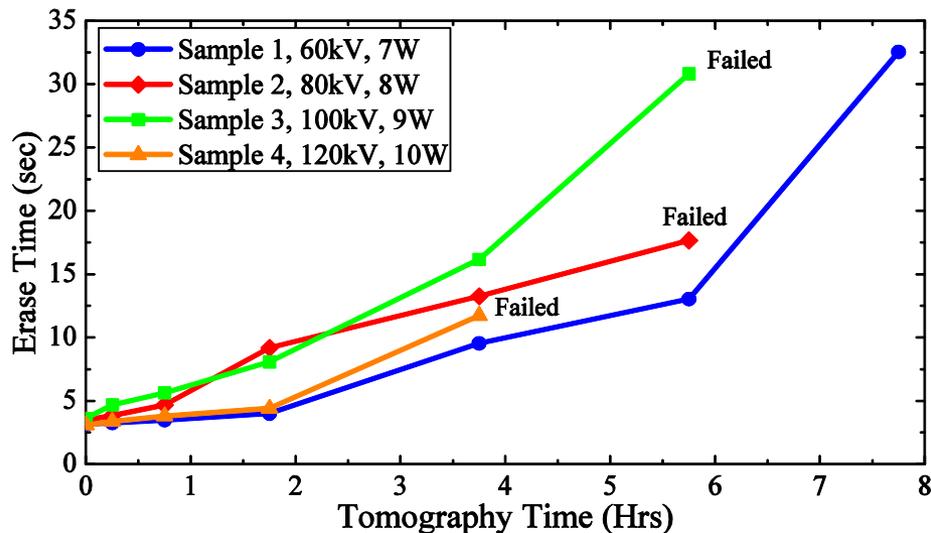
- Xilinx Spartan 3 (90nm Technology)
- Xilinx Spartan 6 (45nm Technology)



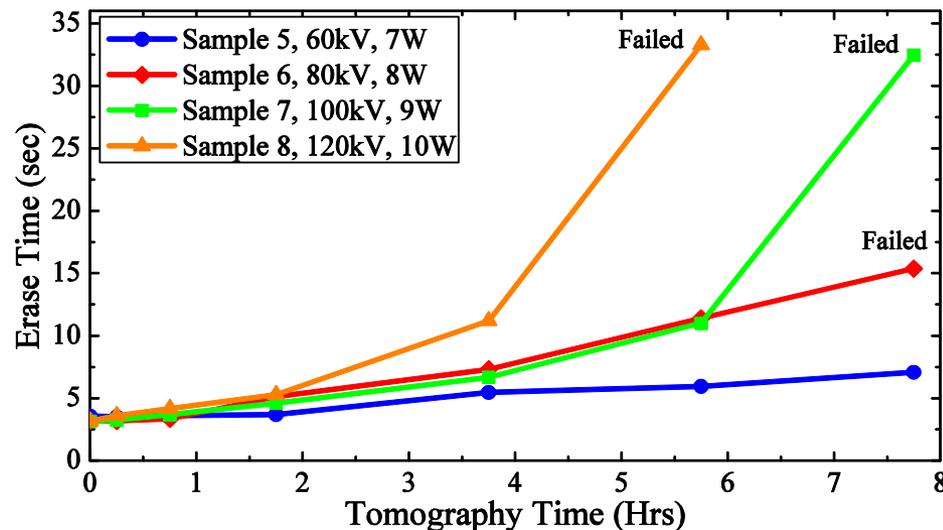
- Total flash memory :
12 (3 sets with 4 ICs in each set)
- Total FPGAs: 4.



Results of Flash Memory



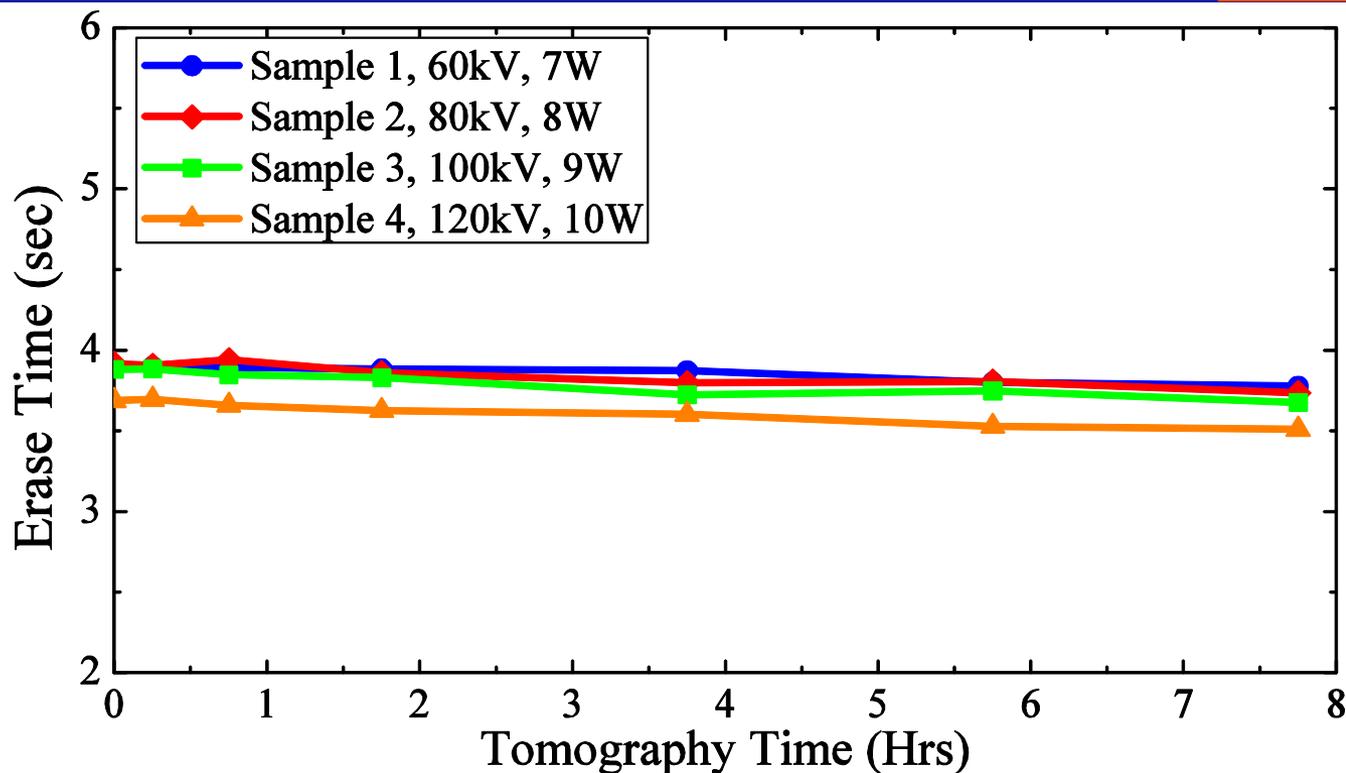
Change in erase time for Set-1 Intel flash memories.



Change in erase time for Set-2 Intel flash memories.

- No bit flip and no change in read margin.
- Read operation is not affected.
- Erase time increased exponentially.
- Failure of erase operation occurred.

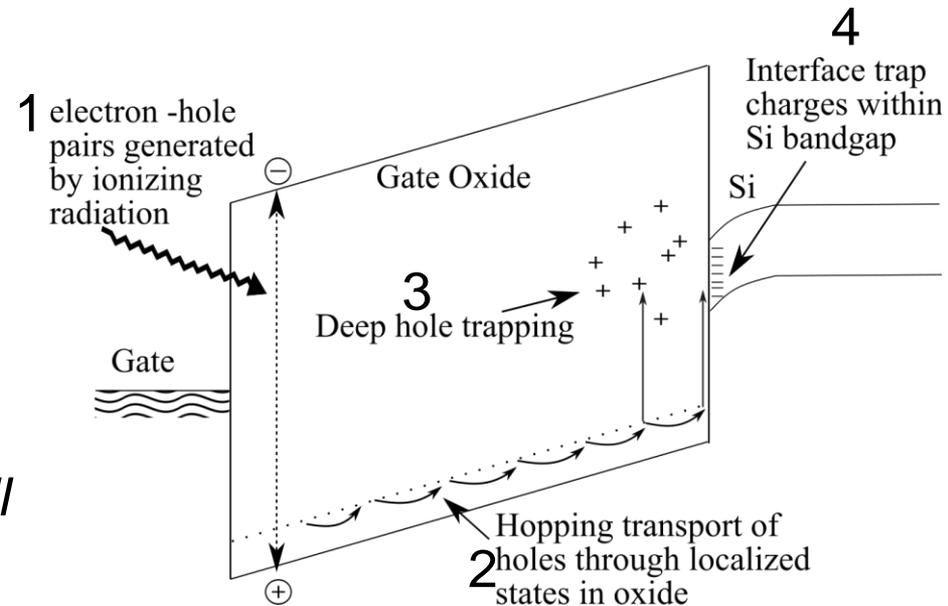
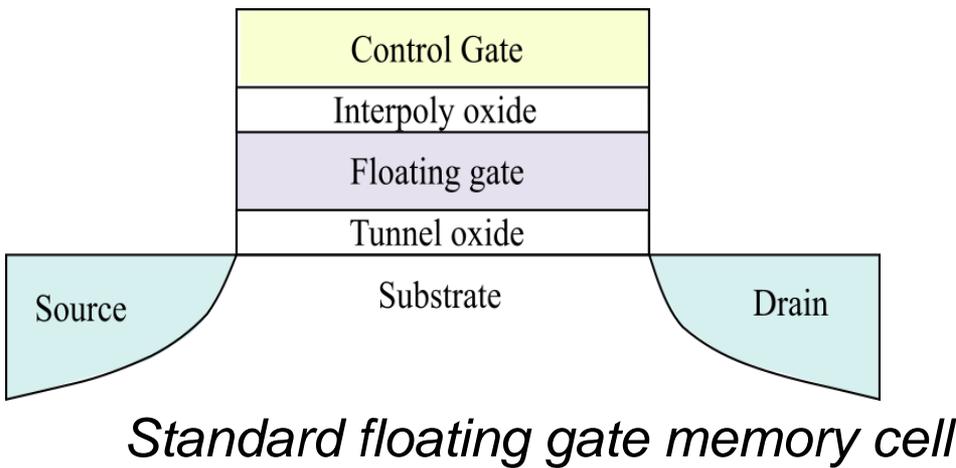
Results of Flash Memory



Change in the erase time for Macronix flash memories.

- Negligible change in Erase time.
- No Failure of erase operation.

Trapped charges in tunnel oxide of Floating Gate Transistor (FG)

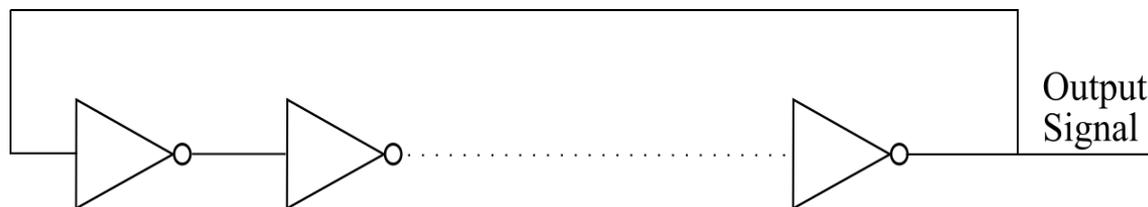


Sources of degradation

Oxide and interface trapped charges.

Electrical Tests of FPGAs

- Tomography was performed at unbiased FPGAs.
- Test focused on the change in the speed of FPGAs.
- Ring Oscillators (ROs) were placed into FPGAs to measure delay of Configurable Logic Blocks (CLB).



RO with odd number of inverters

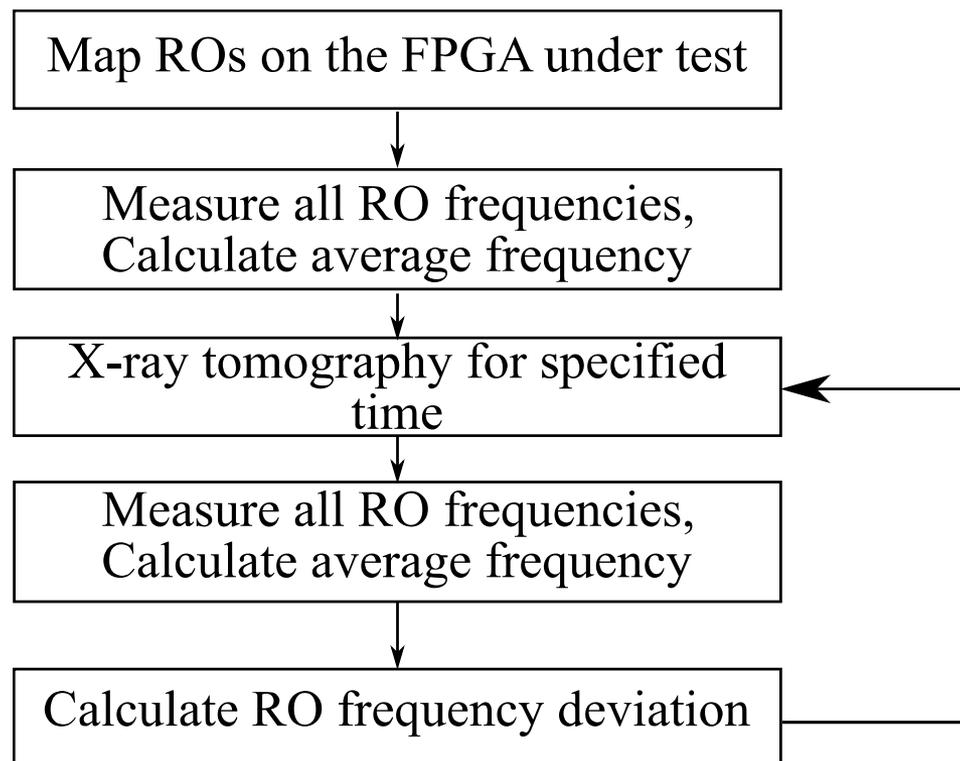
$$f_o = \frac{1}{2 \sum_{i=1}^n \tau_{d,i}}$$

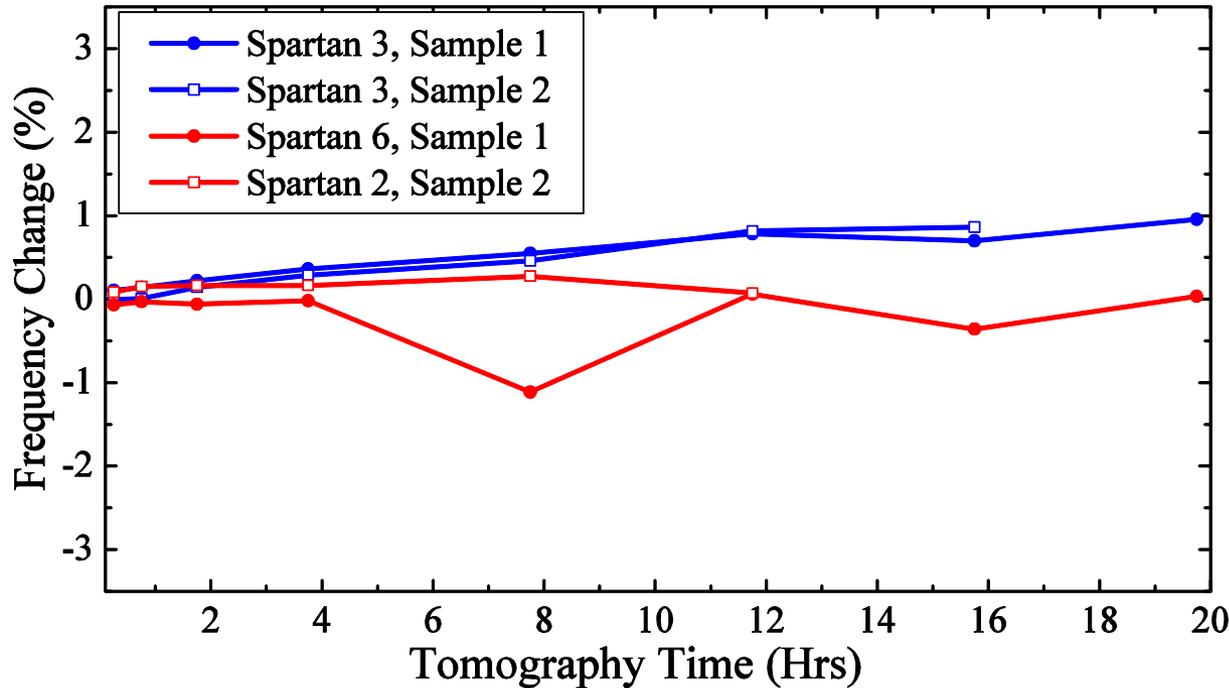
$t_{d,i}$ delay of each element

Frequency Deviation

$$\Delta f_{i,t_n} = 100 \times \left(\frac{f_{i,t_n} - f_{i,t_0}}{f_{i,t_0}} \right)$$

f_{i,t_0} initial frequency of i th RO
 f_{i,t_n} frequency of the i th RO
after the n th tomography
cycle.





Percentage change in the frequency in Spartan 3 and Spartan 6 FPGAs

- Average RO frequency increases with time for both Spartan 3 FPGAs.
- Negligible change until first 4 hours of time in Spartan 6.

- USENIX paper: Printed Circuit Board Deconstruction Techniques
- IEEE TCPMT paper: PCB Reverse Engineering Using Nondestructive X-ray Tomography and Advanced Image Processing
- ISTFA paper: Non-destructive Bond Pull and Ball Shear Failure Analysis Based on Real Structural Properties
- ISTFA paper: Analyzing the impact of X-ray tomography for non-destructive counterfeit detection